

**Charge carrier traps in organic semiconductors: A review on the underlying physics and impact on electronic devices**

Journal:	<i>Journal of Materials Chemistry C</i>
Manuscript ID	TC-REV-10-2019-005695.R1
Article Type:	Review Article
Date Submitted by the Author:	13-Dec-2019
Complete List of Authors:	Haneef, Hamna; Wake Forest University, Physics and Center for Functional Materials Zeidell, Andrew; Wake Forest University, Physics Jurchescu, Oana; Wake Forest University, Physics

1 **Charge carrier traps in organic semiconductors: A review on the underlying** 2 **physics and impact on electronic devices**

3 Hamna F. Haneef,¹ Andrew M. Zeidell,¹ and Oana D. Jurchescu¹

4 ¹Department of Physics and Center for Functional Materials, Wake Forest University, Winston
5 Salem, NC 27109, USA

6

7 **1. Introduction**

8 The promise of low-cost manufacturing, ease of processing, mechanical flexibility and
9 versatility in chemical synthesis make organic semiconductors (OSCs) very attractive as
10 components in electronic and opto-electronic devices. Examples include organic field-effect
11 transistors (OFETs), organic light-emitting diodes (OLEDs), organic photovoltaics (OPV) and
12 sensors.¹⁻⁶ OSCs consist of conjugated molecules containing delocalized electrons resulting from
13 the overlap of π -orbitals. The spatial overlap between the molecular orbitals of adjacent
14 molecules determines the intermolecular electronic coupling and thereby the mechanism of
15 charge transport.^{5,7-9} The intermolecular interactions in the condensed state are weak, mainly
16 consisting of van der Waals forces, as opposed to covalent and ionic bonds prevalent in inorganic
17 solids. As a result, the processing requirements, as well as the mechanical, optical and electronic
18 properties of OSCs, differ considerably from conventional crystalline or elemental
19 semiconductors.^{4,10,11} Binding energies in OSCs are typically low (~ 10 kcal mol⁻¹, for reference,
20 in crystalline Si (c-Si) the energy is ~ 80 kcal mol⁻¹),¹² which makes them attractive for printable
21 electronic applications.¹ Their mechanical properties, coupled with manufacturing in ambient
22 conditions, render them compatible with flexible substrates such as plastic, enabling their use in
23 applications like bioelectronics, display technologies and wearable electronics.

24 OSCs are clearly exciting materials, providing a wealth of technologically attractive
25 properties and intriguing platforms to explore new science, but there are still many unanswered
26 questions and challenges that need to be addressed before their widespread adoption. For
27 example, charge carrier mobilities in OSCs rarely exceed $10 \text{ cm}^2 \text{ V}^{-1} \text{ s}^{-1}$, a value which is orders
28 of magnitude lower than in c-Si or graphene, where mobilities in the order of $10^3 \text{ cm}^2 \text{ V}^{-1} \text{ s}^{-1}$ and
29 $10^6 \text{ cm}^2 \text{ V}^{-1} \text{ s}^{-1}$, respectively, have been reported.¹³ The main reason for such low mobilities is the
30 *localization* of charge carriers, a phenomenon that alters the already narrow bands resulting from
31 van der Waals intermolecular interactions. In the early years of research on organic electronics
32 (1950's), localization of charge carriers in molecular crystals was attributed to polarization
33 whereby charge carriers interact with the surrounding electrons and nuclei in the lattice to form
34 self-localized 'polarons'.¹⁴ The transport of polarons was modelled using the polaron band
35 theory and small polaron theory.¹⁵ Most crystalline OSCs measured in the nineties showed
36 activated transport, which led to the wide acceptance of hopping as the dominant charge
37 transport mechanism in OSCs.^{12,15} Later, observations of power-law temperature dependence of
38 mobilities in high quality single crystals, which is reminiscent of band (delocalized) charge
39 transport, challenged these theories.¹⁵ In the semi-classical description, band transport implies
40 that charge carriers are delocalized over large distances compared to the lattice spacing and are
41 only occasionally scattered by impurities and lattice vibrations. In OSCs however, delocalization
42 of charge carriers is limited to a few molecules, hence the term '*band-like*' was introduced to
43 describe charge transport in these materials.¹⁶ Despite the observation of band-like transport, the
44 mean free path of charge carriers in OSCs is comparable, and sometimes even lower than the
45 intermolecular spacing, supporting localization of charge carriers and consequently low
46 mobilities. This was a rather puzzling contradiction which piqued the interest of the scientific

47 community. Recently it has been shown that dynamic disorder caused by large amplitude thermal
48 motions of molecules is the main factor that limits the mobilities down to a few tens of $\text{cm}^2 \text{V}^{-1} \text{s}^{-1}$.
49 ^{1,13} This type of localization is short lived (*transient* localization) and survives only up to the
50 timescale of the molecular vibrations, which in turn, can be suppressed at sufficiently low
51 temperatures. New models based on a combination of quantum and classical dynamic concepts
52 have been proposed to reconcile the coexistence of band-like/localized charge carriers and
53 establish a proper theory to describe charge transport in OSCs.^{13,17}

54 Localization of charge carriers can be caused by other sources of disorder such as
55 chemical impurities and structural defects (static disorder). In addition, these sources can lead to
56 the formation of electronic states in the band gap of the OSC. These in-gap states can
57 subsequently trap charge carriers and hinder their transport, further preventing the OSC from
58 realizing their intrinsic mobilities. Charge carrier trapping is a ubiquitous phenomenon that has
59 repercussions on the performance and stability of OSC opto-electronic devices, as well as on our
60 ability to access their intrinsic properties. Understanding the mechanisms and processes related
61 to trap formation, the dynamics and timescales over which these processes occur is decisive in
62 extracting fundamental performance limits of OSCs and subsequently engineering high-
63 performance devices. This article aims to provide a comprehensive and timely review on the
64 phenomenon of charge carrier trapping in OSCs, with emphasis on its impact on device
65 operation. Starting with the definition of traps in Section 2, we continue by describing the
66 different origins of traps in OSCs (Section 3), followed by a discussion on the effect of traps on
67 the performance of organic opto-electronic devices (Section 4) and on the mechanism of charge
68 transport in OSCs (Section 5). An overview of the experimental techniques available to detect
69 and characterize traps will be provided in Section 6. Charge carrier traps can also be viewed as

70 an opportunity for advanced detection: in Section 7, we discuss the exploitation of traps for
71 organic-electronics-based sensing and memory applications.

72

73 **2. What are charge carrier traps?**

74 Before we move onto the description of traps, we introduce the density of states (DOS)
75 function, which describes the energetic distribution of electronic states within energy bands. In a
76 perfectly-ordered, crystalline semiconductor, such as c-Si, the density of delocalized (extended)
77 states takes the form of a lying parabola ($E^{1/2}$ dependency, where E is the energy of an electronic
78 state) with well-defined band edges and hence a band gap (see Figure 1a).¹⁸ In semiconductors
79 with weak localization, such as amorphous Si (a-Si), the extended states tail into the band gap to
80 create localized states as shown in Figure 1b.¹⁹ These tail states are often modelled by an
81 exponential function.^{20,21} In this case, an energy gap and band edges cannot be precisely defined;
82 instead a *mobility-edge* that separates extended states from localized states was introduced.^{19,22} In
83 disordered semiconductors, the localization is strong and the DOS is typically approximated with
84 a Gaussian distribution (Figure 1c) or an exponential distribution (Figure 1d).^{20,23} The highest
85 occupied molecular orbital (HOMO) and the lowest unoccupied molecular orbital (LUMO) are
86 analogous to the top of the valence band and bottom of the conduction band, respectively. These
87 terms will be used interchangeably throughout this review. For a Gaussian shaped DOS, an
88 *effective transport energy* is defined as the energy at which a charge carrier equilibrates over
89 time after multiple hopping between the localized states.^{19,24} The onset of the HOMO and
90 LUMO are defined at the onset of the Gaussian when the tangent through the inflection point
91 crosses the baseline (see Figure 1c).^{11,19} Depending on the extent of localization of charge
92 carriers, which is decided by various factors such as the molecular structure, molecular packing

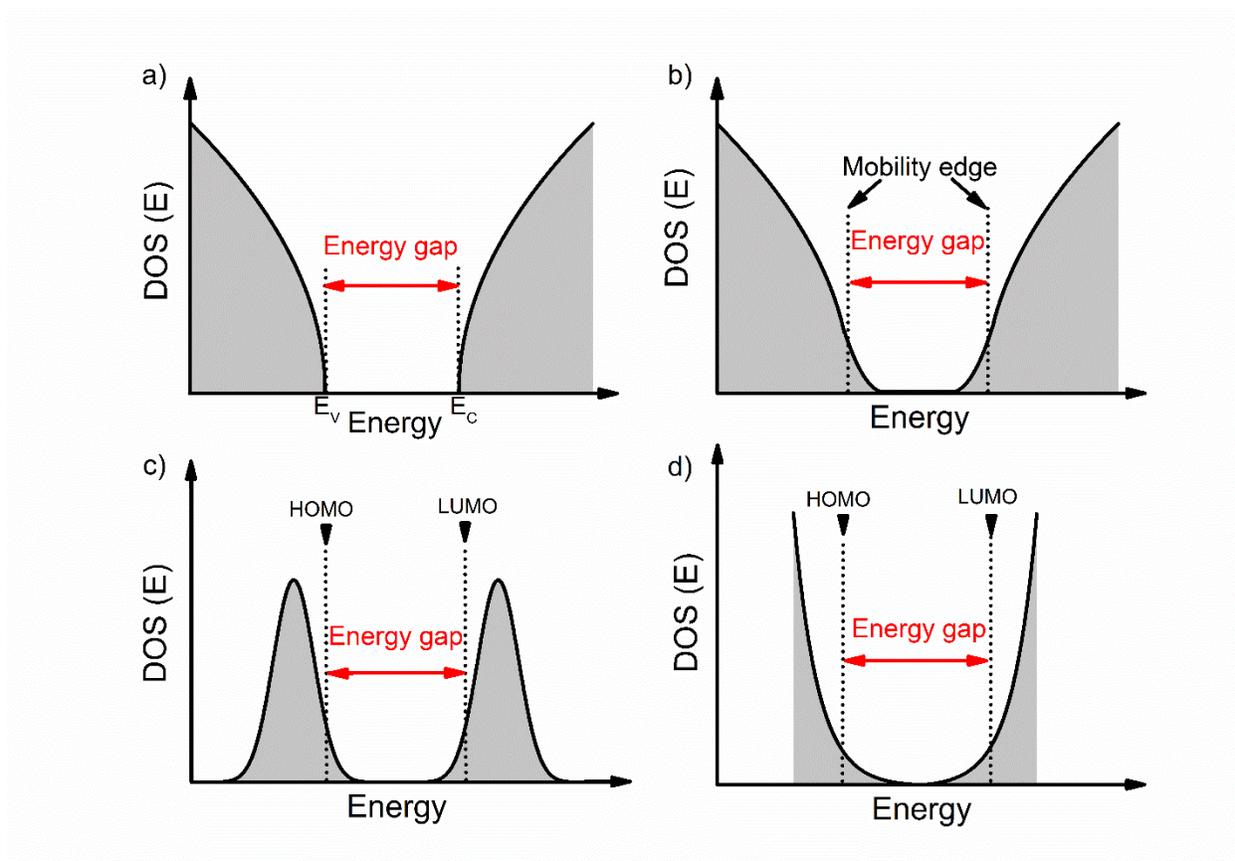
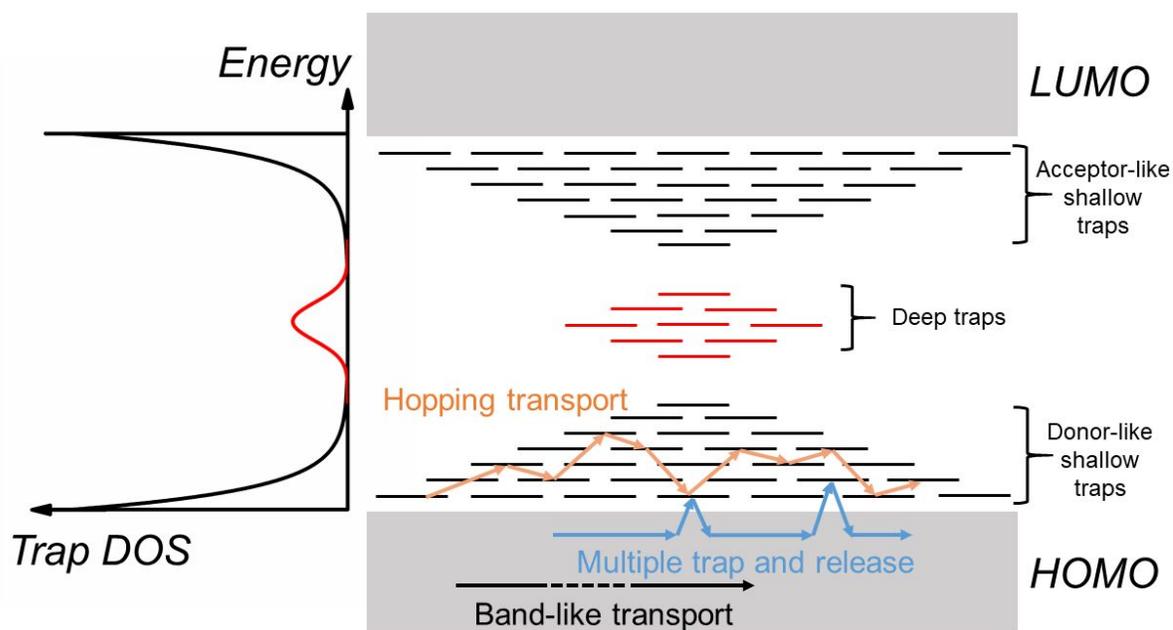


Figure 1. Extended states DOS function of a) crystalline OSCs, b) crystalline OSCs with weak localization, and c), d) polycrystalline/amorphous OSCs assuming Gaussian and exponential models, respectively.

93 and the extent of disorder, the shape of the DOS function can be approximated to one of the four
 94 forms illustrated in Figure 1. Ideal, perfectly-ordered single crystals adopt the DOS shape in
 95 Figure 1a; however, the disorder induced by thermal molecular motions (discussed in Section
 96 3.1) gives rise to tail states in the band gap and therefore their DOS is better approximated by the
 97 curve in Figure 1b.^{13,25–27} Figure 1c and Figure 1d are typically used to represent the DOS in
 98 polycrystalline and amorphous OSC films.^{11,20,23,28}

99 An *electronic trap* is any imperfection in the semiconductor that creates localized
100 electronic states spatially distributed around the site of the imperfection and energetically
101 distributed within the band gap of the semiconductor. Depending on their relative energetic
102 positions from the band edge (trap depth) at a given temperature, traps can be *shallow* if located
103 in the vicinity (a few kT) of the band edges, or *deep* if they lie further (several kT) from the band
104 edges as illustrated in Figure 2, where k is the Boltzmann's constant and T the temperature.
105 Localized tail states in the band gap are generally considered shallow traps, with acceptor-like
106 states near the LUMO edge and donor-like states near the HOMO edge representing trap states
107 for holes and electrons, respectively. A trap can capture and restrain a charge carrier temporarily
108 until it is released back into the band by an external stimulus such as electric field, thermal
109 energy or a photon. For example, in the multiple-trap and release (MTR) model, charges moving
110 within delocalized states are trapped by a localized shallow trap state in the band gap, then
111 released back into the energy band by thermal energy as depicted by the blue arrows in Figure
112 2.^{29,30} A band-like motion (which occurs within delocalized states) is also illustrated in Figure 2,
113 in black arrows, for comparison. If the trap densities are high, trapped charge carriers can
114 participate in transport through thermally-activated hopping or tunneling from one localized state
115 to another (orange arrows in Figure 2).³¹ Thermal detrapping of charge carriers is possible if the
116 trap depth is sufficiently low ($\sim kT$); charge carriers residing in shallow traps at a given
117 temperature are more likely to get thermally excited back into the band, while those in a deep
118 trap have a negligible probability of being thermally excited.³² Such deep states often act as
119 recombination centers for charge carriers reducing their overall lifetime.

120 A DOS function to represent localized electronic states within the band gap of an OSC
121 can be defined. Such a function is referred to as *trap DOS*. Traps can have discrete energy levels



122

Figure 2. (Left) The trap DOS function represents shallow traps resulting from tail states (black) and deep traps (red) in the band gap. (Right) Schematic spatial and energy diagram of an OSC containing localized trap states in the band gap. Tail states forming acceptor-like and donor-like shallow traps are shown in black, while deep traps are shown in red. Arrows represent different transport regimes possible in an OSC; band-like transport (black), MTR (blue) and thermally-activated hopping transport between localized states (orange).

123 or a quasi-continuous energy distribution that is often described using an exponential or a
 124 Gaussian function.^{33–36} The left panel of Figure 2 illustrates a Gaussian distribution of trap states
 125 deep in the band gap (red curve) in addition to the disorder-induced tail states (black curve)
 126 extending into the band gap, and which act as shallow traps.

127

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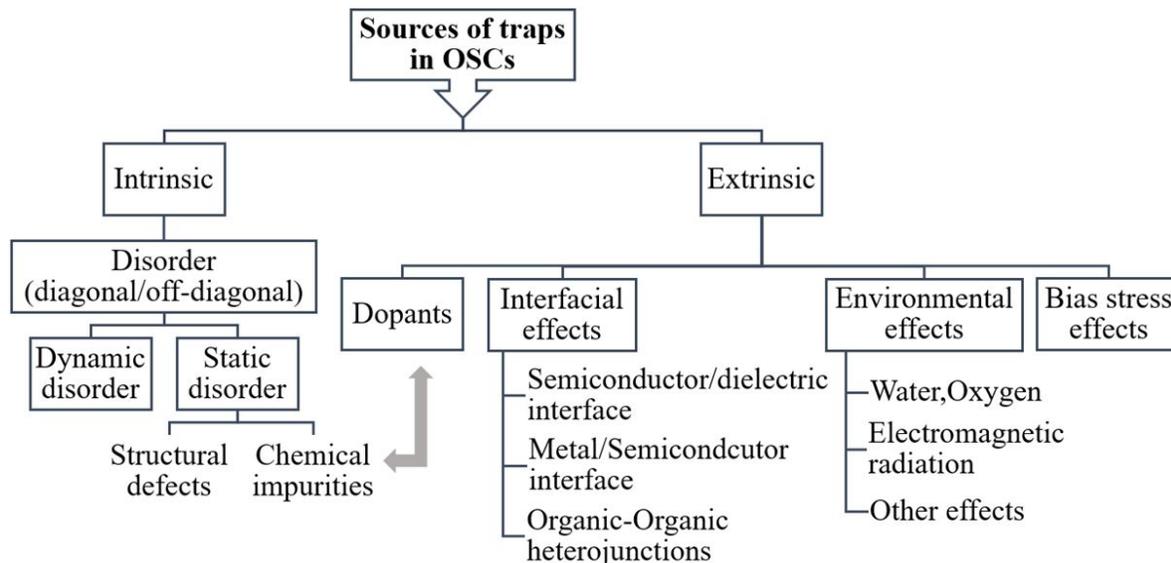


Figure 3. Sources of charge carrier traps in OSCs.

129

130 3. Sources of traps in organic semiconductors

131 Electronic traps in OSCs can originate from varying sources, as summarized in the
 132 scheme in Figure 3. The main source of traps in OSCs is disorder. Structural defects and
 133 chemical impurities cause static disorder and are considered *intrinsic* sources of traps in OSCs.
 134 They form during or after crystal/film formation and can be minimized through careful control of
 135 the growth process. In addition, dynamic disorder is an intrinsic source of traps. *Extrinsic* traps
 136 can be intentionally or unintentionally introduced by either exposure to gases, electromagnetic
 137 radiation, temperature gradients, bias stress, dopants, or by interfacing with other materials such
 138 as a metal, dielectric or another OSCs. Since the energetic landscape involved in the presence of
 139 inadvertent chemical impurities and deliberately added dopants is similar, dopants will be
 140 discussed in the context of chemical impurities. In this section, we will discuss each type of traps

141 included in the scheme and will provide examples on how they impact material and device
142 properties.

143

144 **3.1. Disorder**

145 Perturbations or imperfections in the crystal structure, existing either in a single unit cell
146 or extending over several unit cells, can locally destroy the crystal and translational symmetry,
147 thereby introducing disorder into the system. The spatial distribution of structural properties such
148 as intermolecular electronic coupling results in *structural* disorder, also called *off-diagonal*
149 disorder.⁸ If the disorder translates into fluctuations in site energy (i.e., HOMO or LUMO energy
150 level) of a molecule or molecular segment, it is referred to as *energetic* disorder or *diagonal*
151 disorder.⁸ Any structural disorder in the cartesian domain will inevitably give rise to energetic
152 disorder in the energy domain.²⁴ Energetic disorder is often modelled by a Gaussian distribution
153 of energy with a standard deviation quantifying the extent of disorder.³⁷ An exponential DOS is
154 also used to model disorder-induced tail states in the band gap.^{20,21}

155 The disorder can be *dynamic* or *static*: dynamic disorder is caused by thermal motions of
156 the molecules (intermolecular and intramolecular), i.e. from electron-phonon interactions, while
157 static disorder is caused by structural defects (Section 3.1.1.) and chemical impurities (section
158 3.1.2.). The major difference between the two is that the former results in time-dependent
159 variations in the site energies and transfer integrals and occurs throughout the entire crystal,
160 while the latter is time-independent and occurs only at specific locations where the defects are
161 present. Dynamic disorder can destroy the already narrow electronic energy bands, resulting in
162 localization of charge carriers. However, the disorder lasts only up to the timescale of the

163 thermal motions (hence the term ‘*transient localization*’) and can be sufficiently reduced at low
164 temperatures.¹³ Static disorder can also result in charge carrier localization (Anderson
165 localization) arising from the variations in electron potentials.³⁸ Both dynamic disorder and static
166 disorder introduce localized tail states in the band gap, with the latter creating additional in-gap
167 states due to the presence of structural inhomogeneities. Tail states induced by dynamic disorder
168 form even in nominally perfect OSC single crystals and represents the major performance
169 limiting factor in such materials.^{27,39} Moreover, the density of tail states resulting from large
170 amplitude thermal motions is much higher than those resulting from structural inhomogeneities,
171 and hence they play a key role in determining the details of charge transport in materials in
172 which the electronic coupling between molecules is weaker compared to the electron-phonon
173 coupling.⁴⁰ A discussion on the effect of disorder on charge transport is beyond the scope of this
174 review and the reader is directed to the rich literature existing on the subject.^{8,13,17,37,41–43} In this
175 review, the discussion will be limited to the disorder-induced gap states that can potentially trap
176 charge carriers. Theoretical calculations confirmed the existence of a tail of gap states near the
177 valence band edge resulting from thermal molecular motions.^{25,44–46} In pentacene, for example,
178 the states were modelled exponentially to yield a tail breadth of 6.9 meV at 100 K, increasing to
179 12.7 meV at 300 K due to higher amplitude thermal motions at elevated temperatures.²⁵ By using
180 a combination of temperature-dependent FET and charge modulation spectroscopy (CMS)
181 measurements Sirringhaus and coworkers confirmed that dynamic disorder induces shallow
182 traps.⁴⁷ They found that the degree of localization is sample dependent and charge carriers are
183 highly localized in pentacene films, a phenomena that does not occur in 2,8-difluoro-5,11-
184 bis(triethylsilylethynyl) anthradithiophene (diF-TES ADT), even at low temperatures. Band gap
185 tail states have been experimentally observed in several materials such as single crystals of

186 rubrene and their derivatives, but their precise origin remains unclear^{48,49}. Troisi and co-workers
187 pointed out that they are similar to those detected in inorganic semiconductors which result from
188 intrinsic electronic disorder.¹⁵ Experimental evidence on the presence of gap-states due to static
189 disorder and their role in charge carrier trapping will be provided in the succeeding sections
190 (3.1.1 and 3.1.2).

191

192 **3.1.1. Structural defects**

193 Structural inhomogeneities within the OSC can yield intrinsic traps. Here we begin with
194 the discussion of such defects in OSC single crystals and later extend the discussion towards thin
195 films. Structural imperfections in the form of lattice defects exist in every real crystal and the
196 number of such defects depends on the method as well as the rate of crystal growth.⁵⁰ Crystal
197 defects can be categorized as point defects or extended defects. While the former reside at a
198 specific lattice site (e.g. vacancy), the latter extend over several lattice sites. Extended defects
199 can be in the form of line defects such as dislocations, or planar defects such as stacking faults.
200 Each molecule located in the vicinity of the defect(s) is displaced from its equilibrium position
201 and a charge carrier residing on such a molecule will experience a change in its electronic
202 polarization energy, P . Variations in the local electronic polarization energies for charge carriers
203 in the vicinity of such defects result in the formation of localized trapping states with energies
204 distributed quasi-continuously in the band gap.³³ Localized states with higher electronic
205 polarization energy ($\Delta P > 0$) are formed in compressed regions of the lattice and act as charge
206 carrier traps. In expanded regions of the lattice, e.g. in the vicinity of a vacancy, localized states
207 with lower electronic polarization energy ($\Delta P < 0$) can be created below/above the

208 HOMO/LUMO levels. While these states are energetically inactive for charge carrier trapping,
209 hence called anti-traps, they can hamper transport by acting as scattering centers for charge
210 carriers. In addition to changes in electronic polarization energies, structural defects also cause
211 changes in electronic coupling between molecules. In compressed regions of the lattice, the
212 electronic coupling between molecules is stronger due to the narrower spacing between them.
213 Likewise, weaker electronic couplings exist in dilated regions of the lattice.

214 *Dislocations* in molecular crystals have been studied since the early 70's.^{33,51–54} Thomas
215 and Williams showed that in anthracene crystals molecules residing within ca. 400 Å radius from
216 the site of dislocation act as traps for holes.⁵² Dislocations in naphthalene crystals have been
217 identified by Lohman and Wehl as electron traps.⁵³ The density of dislocations mainly depends
218 on the growth technique; vapor-grown crystals typically have a lower dislocation density
219 compared to crystals grown from the melt or solution.⁵² In addition to being a charge trapping
220 site by itself, edge dislocations readily accommodate impurities around their core, potentially
221 creating additional trapping states.⁵²

222 *Step edges* were identified as electron traps in single crystals of N, N'-bis-
223 (heptafluorobutyl)-2,6-dichloro-1,4,5,8-naphthalene tetra- carboxylic diimide (Cl₂-NDI) using
224 scanning Kelvin probe microscopy (SKPM).⁵⁵ It was found that the OFET threshold voltages and
225 mobilities depended strongly on the density of step edges, with the former decreasing and the
226 latter increasing with increased step densities.

227 *Grain boundaries* (GBs) present in OSC thin films add to structural defects within the
228 grain and hamper charge carrier transport,^{56–61} although some exceptions exist.⁶² The discussion
229 of whether they act as traps or energy barriers for charge carriers has been controversial, both

230 phenomena resulting in thermally-activated transport.^{32,63} Spatially resolved techniques were
231 adopted to access the local nature of trapping in polycrystalline thin films. Marohn and
232 coworkers used electron force microscopy to study the spatial distribution of traps as a function
233 of gate-source voltage in pentacene thin-film transistors.^{64–66} They found that the traps are not
234 only concentrated on grain boundaries, but distributed throughout the film. On the other hand,
235 using scanning probe microscopy measurements, Frisbie and coworkers observed that the surface
236 electrostatic potential at GBs is lower than that in the crystallites, which indicates that holes are
237 predominantly trapped at GBs.⁶⁷ This result is in agreement with the work by Horowitz et al. and
238 Sirringhaus and coworkers.^{68,69} Kaake et al. suggested that charge carriers are trapped within the
239 grains, while the surrounding grain boundaries act as insulating barriers for the trapped charge
240 carriers preventing them from crossing the grain boundaries.⁶³ Their interpretation was based on
241 the weaker electronic coupling between molecules located in grain boundaries compared to those
242 located inside the grains, a phenomenon that pushes the HOMO and LUMO levels into the band
243 rather than into the band gap and hence does not cause charge carrier trapping. Teague et al.
244 detected a pronounced potential drop at GBs,⁷⁰ in agreement with earlier studies which found an
245 order of magnitude larger resistance across the grain boundaries than within the grains.⁷¹ The
246 existence of different types of GBs resulting from different processing conditions, as indicated
247 by Lee et al. and Jimison et al., might be the cause of such different responses.^{72,73}

248 Structural defects in the form of *stacking faults* were detected in pentacene thin-films
249 using a combination of electronic structure calculations and scanning tunneling microscopy.⁷⁴ It
250 was proposed that compressive stress during film growth causes the molecules to slide along
251 their long-axis, leading to larger molecular overlap, which results in the formation of shallow
252 traps with energies ≤ 100 meV close to the band edges. In solution deposited small molecule

253 OSCs, this type of defect was healed by introducing gentle vibrations during crystallization, and
254 a reduction in the density of trap states was confirmed by spectral analysis of the trap density of
255 states.⁷⁵ *Line dislocations* have been identified in pentacene thin films by using a combination of
256 scanning probe microscopy and chemical etching.⁶⁷

257 In polymers, conformational defects such as *kinks* in the backbone can introduce both
258 shallow and deep trapping states.^{76,77} The *kinks* can break the conjugation and generate energetic
259 disorder resulting in a sequence of conjugated segments each having different HOMO and
260 LUMO levels,. Synthesis routes to minimize the energetic disorder in amorphous polymers have
261 been proposed. For example, the synthesis of the polymer poly(para-phenylene) (PPP) by
262 planarization of the polymer backbone (ladder polymer) yielded well-defined conjugation length
263 and interchain order resulting in high-performance OLEDs.⁷⁷ In indacenodithiophene-
264 benzothiadiazole (IDT-BT), a donor-acceptor copolymer that has gained a lot of attention lately
265 for its high charge carrier mobilities,⁷⁸ the performance is obtained in spite of its low
266 crystallinity.⁷⁹ These electrical properties that are approaching a trap-free limit result from an
267 efficient transport along the rigid backbone, with occasional hopping through π -stacks. In fact,
268 even though amorphous polymers lack long-range order, they contain ordered crystalline
269 domains that obey the Physics of crystalline polymers.⁸⁰ Karki et al. used solid state nuclear
270 magnetic resonance (NMR) spectroscopy to quantify the relative densities of ordered and
271 disordered regions of two structurally distinct polymer films highlighting the impact of the
272 molecular structure on the degree of order.⁸⁰

273

274

275 3.1.2. Chemical impurities/dopants

276 The presence of guest molecules in the form of inadvertently existing chemical impurities
277 (formed upon chemical degradation, synthesis byproducts), or deliberately added dopants in a
278 host, can introduce trapping states with a broad range of energies in the band gap. The energy
279 levels of the guest molecule are, in general, different than that of the host and these differences is
280 the basis for the formation of such states. On zero-order approximation, the localized trapping
281 states can be considered to be discrete. Hence, for hole traps, the energy of the trapping state, E_t^h ,
282 is determined by the difference between the ionization energy (\sim energy of the HOMO level) of
283 the guest and that of the host. Similarly, for electron traps, E_t^e is the difference in electron
284 affinity (\sim energy of the LUMO level) between the guest and the host, i.e.,

$$E_t^h = I_G - I_H \quad (1)$$

$$E_t^e = A_G - A_H \quad (2)$$

285 Where I and A are the ionization energy and the electron affinity of the respective molecules,
286 denoted by the subscripts G and H which stand for guest and host molecules respectively, and e
287 represent electrons and h holes. In addition, a difference in the electronic polarization energy of
288 the host and guest molecules (ΔP), caused by the distortion of the host lattice due to the presence
289 of the guest molecule, can also, to some degree, impact the energy of the trapping state. Whether
290 or not the lattice is compressed or dilated decides the sign of ΔP as mentioned earlier. ΔP is
291 found to be within 0.1 eV and is generally ignored to obtain the simplified equations 1 and 2,
292 except for the case of deep trapping caused by impurities, where ΔP is significant.³³

293 Figure 4 illustrates several hypothetical situations in which charge carrier trapping or
294 anti-trapping states are formed by the presence of guest molecules in a host lattice. In the first

295 case (Figure 4a), the HOMO and the LUMO levels of the guest are positioned within the band

296 gap of the host, therefore generating trap states for both holes and electrons. For anthracene

297 crystals doped with tetracene guest molecules, Karl showed that hole traps formed at 0.42 eV

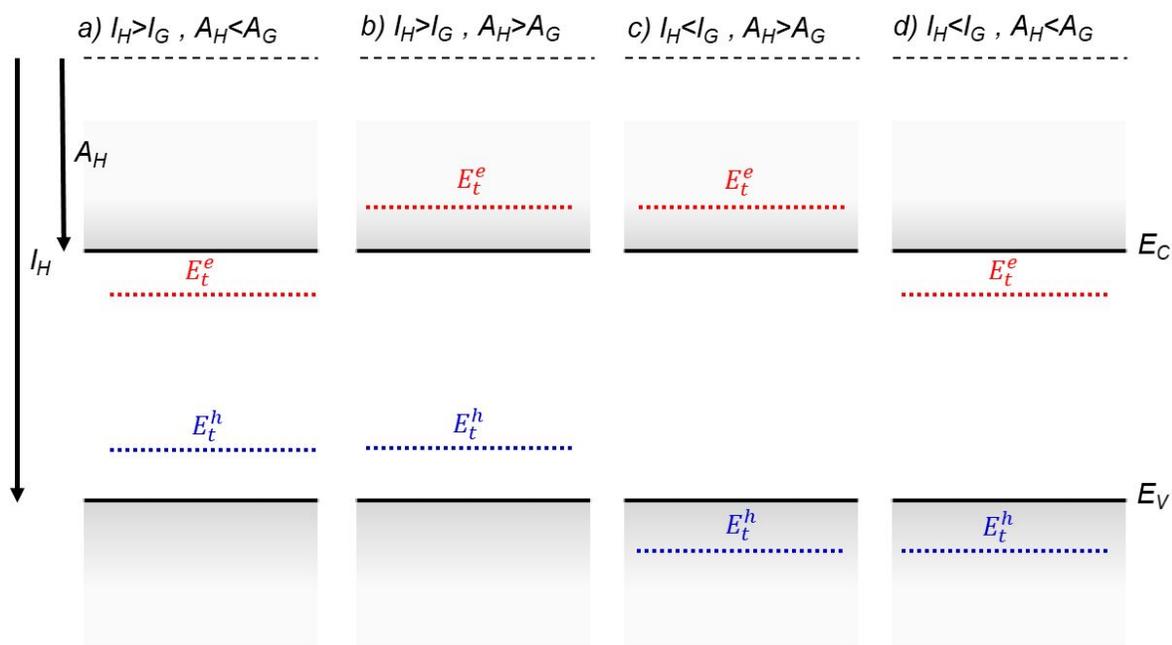


Figure 4. Charge carrier trapping and anti-trapping states resulting from the presence of a guest molecule in a host lattice. Additional in-gap states are not shown for clarity. Solid lines represent the band edges of the host molecule and broken blue lines and red lines represent discrete trapping states for holes and electrons respectively. a) trap state for both holes and electrons, b) trap state for holes and anti-trap state for electrons, c) anti-trap state for both holes and electrons and d) anti-trap state for holes and trap state for electrons.

298 form the valence band edge and electron traps at 0.12-0.17 eV from the conduction band edge.⁸¹
 299 An order of magnitude reduction in the hole mobilities was observed even with 0.5 ppm of
 300 tetracene as a result of the dominant hole trapping.⁸² The transport mechanism was band-like for
 301 the pristine crystal, as determined from time of flight measurements, and MTR for the crystal
 302 doped with tetracene. In Figure 4b, the guest molecule introduces trap states only for holes, such
 303 as in the case of anthracene crystals doped with phenothiazine, where the trap was detected at 0.8
 304 eV from the HOMO level using time of flight measurements.⁸³ The example illustrated in Figure

305 4c presents a chemical impurity with ionization energy greater than, and electron affinity less
306 than those of the host. Such an impurity is energetically inert. Even though this type of impurity
307 is not directly associated with charge carrier trapping, it still contributes to a local distortion of
308 the lattice and can act as a scattering center for charge carriers. The concentration of the
309 impurities or dopants will determine the total scattering events. Tetracene molecules in an
310 anthracene host is such an example, where anti-traps for both electron and holes are
311 formed.^{33,81,83} Finally, panel 4d describes the case when the guest molecule introduces trap states
312 for electrons only. Using time of flight measurements, Karl detected electron trapping in
313 anthracene crystals doped with acidine, phenazine and anthraquinone at energies 0.2 eV, 0.54 eV
314 and 0.6 eV respectively from the conduction band edge.⁸¹

315 Chemical degradation can also lead to the formation of traps. Oxidation is one of the most
316 common forms of degradation in OSCs. In the case of acene crystals, oxidation leads to the
317 formation of quinones. In anthracene and tetracene crystals, the respective quinones form deep
318 traps for electrons, as confirmed by photoemission measurements.³³ Photo-oxidation of the
319 crystals resulted in an increased concentration of such impurities. In pentacene single crystals,
320 pentacenequinone acts as an energetically inert impurity, similar to the example included in
321 Figure 4c, but its presence lowers the charge carrier mobilities by locally distorting the lattice.⁸⁴
322 Reduction of the impurity content by a factor of five lead to two orders of magnitude lower trap
323 density, and mobilities as high as $35 \text{ cm}^2 \text{ V}^{-1} \text{ s}^{-1}$. Environmental contaminants such as moisture
324 (H_2O) and O_2 can also create discrete trap states. The high electron affinity of O_2 gas molecules
325 make them potential traps for electrons.⁸⁵ Isolated H_2O and O_2 gas molecules cannot trap holes as
326 their gaseous phase ionization energies are too high ($\sim 12 \text{ eV}$).⁸⁶ However, clusters of water
327 molecules have significantly lower ionization energies due to stabilization of charge from the

328 dipole moment of surrounding molecules and hence can form potential traps for holes.^{86,87}

329 Examples of such traps will be discussed in section 3.3.

330 Dopants are often added to OSCs to enhance their conductivity. The doping efficiency is
331 governed by several factors such as the offset of energy levels between the host and the guest and
332 the dopant concentration. The mechanism of charge transport in doped OSCs is complex and is
333 dominated by several competing processes that depend on the above factors. For example, the
334 addition of a dopant can either broaden the DOS of the host thereby introducing tail states, or the
335 dopant-induced charge carriers can fill up existent trap states to neutralize them or the presence of
336 the dopant can annihilate the trap states.⁸⁸⁻⁹¹ For a detailed description of doping in OSCs and
337 different types of doping such as molecular and metallic doping, we recommend the review by
338 Lüssem et al.⁹²

339

340 **3.2. Interfacial effects**

341 Organic electronic devices consist of consecutive layers of dissimilar electronic materials
342 and their architecture has different complexity levels depending on the function that they
343 perform. The phenomena occurring at interfaces between any two distinct layers, such as
344 electrode/semiconductor, semiconductor/dielectric and interface with other organic layers, add to
345 the charge carrier trapping discussed in Section 3.1, which focused on the processes occurring in
346 the bulk of the OSC. Trapping at interfaces has a profound impact on device performance, as we
347 will describe in this section.

348

349 **3.2.1. Traps at semiconductor/dielectric interface**

350 In OFETs the transistor channel forms in the vicinity of the gate dielectric and the
351 presence of charge carrier traps at the interface between the OSC and dielectric can impact the
352 performance of such devices.¹⁰ For example, in addition to scattering of the accumulated
353 charges due to non-uniform topology,^{93,94} surface energy and chemistry, the roughness of the
354 dielectric layer alters the molecular ordering of the OSC deposited on top, which results in
355 structural defects such as dislocations. Chua et al. investigated the effect of interface roughness
356 on the charge carrier mobility in OFETs and found that for small values the mobility did not vary
357 significantly, but above a critical roughness of 0.7 nm, it decreased by several orders of
358 magnitude.⁹⁵

359 Another route for trap generation at the semiconductor/dielectric interface is related to the
360 adsorption of impurities such as water, oxygen or hydroxyl groups. The passivation of dangling
361 bonds at the surface of the SiO₂ gate-dielectric by adsorption of hydroxyl groups results in a high
362 density of silanol groups at the surface that can trap electrons. This has been the main challenge
363 in achieving electron transport in SiO₂-based transistors.^{93,96} The application of self-assembled
364 monolayers (SAMs) such as hexamethyldisilazane (HMDS), octadecyltrichlorosilane (OTS),
365 and decyltrichlorosilane (DTS) has proven to passivate some, (but not all) of the surface traps in
366 SiO₂ to yield functional n-channel OFETs.⁹⁶ Stable operation of the devices was realized with
367 the use of polyethylene as a dielectric buffer layer.⁹⁶ Fluorinated polymer dielectrics such as
368 Cytop and poly[4,5-difluoro-2,2-bis(trifluoromethyl)-1,3-dioxole-co-tetrafluoroethylene]
369 (AF2400) allow for a significantly lower interfacial trap density compared to SiO₂.^{97,98} Also, the
370 fluorine group renders them hydrophobic and hence they can repel water molecules,^{99,100} and
371 when used as top gate dielectrics, they also act as encapsulants.

372 The effect of the gate dielectric type on the performance of pentacene thin film transistors
373 has been investigated by Knipp et al.¹⁰¹ The transfer characteristics was modelled by a trap DOS
374 consisting of two exponential distributions of deep acceptor-like states and donor-like shallow
375 states,²⁰ with the former accounting for the onset of drain current while the latter accounts for a
376 non-zero threshold voltage. The nature of the dielectric affected film microstructures which, in
377 turn, determined the density and the depth of the trap DOS. For example, films on
378 benzocyclobutane (BCB) consisted of smaller grains than those on SiO₂ and yielded a more
379 negative threshold voltage due to a broader distribution of donor-like shallow trap states, with
380 the width increasing from 45 meV on SiO₂ to 90 meV on BCB. Modification of film
381 microstructure has also been achieved by treatment of the substrate with SAMs, leading to lower
382 trap densities and therefore high charge carrier mobilities.¹⁰² SAMs such as OTS and
383 octadecyltrichlorosilane (ODTS) provide a low-surface energy, which typically yields a better
384 film morphology, but they are challenging to implement in solution-deposited devices.^{103,104}

385 Mei et al. discovered that the mismatch in the coefficient of thermal expansion (CTE) of
386 consecutive device layers induces strain at the interfaces, which results in generation of localized
387 trapping states.¹⁰⁵ They found a crossover from a band-like transport to a temperature activated-
388 transport upon increasing the interfacial thermal expansion mismatch, which could not be
389 explained by polaronic effects alone,^{106–108} and was assigned to charge trapping due to thermal
390 strain.

391 The above effects arising at the semiconductor/dielectric interface vanish in the case of a
392 transistor with a vacuum-gap dielectric, as demonstrated by Sundar et al. and Menard et al. using
393 polydimethylsiloxane (PDMS) stamps as substrates.^{109,110} However, the CTE mismatch between
394 the PDMS substrate and the OSC can introduce microstrain in the crystal, which in turn modifies

395 its work function.¹¹¹ Such modifications can potentially create band tail states induced by
396 electrostatic disorder.

397

398 **3.2.2. Metal/semiconductor interface**

399 Charge carrier trapping can also occur at the interface between device electrodes and
400 OSCs, thus affecting charge carrier injection and collection. The localized states present in the
401 band gap of an OSC can alter the mechanism of charge carrier injection from the metal into the
402 OSC, resulting in an increased injection barrier that manifest itself as high contact resistance in
403 electronic devices. Such states can be intrinsic to the OSC, or can be introduced by the metal.¹¹²
404 The energetic disorder inherent in most OSCs causes some of the in-band electronic states to tail
405 into the bandgap,¹¹³ which can pin the Fermi level of the metal and prevent it from reaching the
406 band edges resulting in non-vanishing injection barriers. The extent of disorder determines the
407 distance from the band edge to the pinned Fermi-level. Insertion of a buffer layer, such as a thin
408 oxide metal layer, between the metal and the OSC, can unpin the Fermi-level decreasing the
409 injection barrier.¹¹⁴ On the other hand, these gap states can also act as energy ladders for charge
410 carriers to hop between these states and reach the transport energy level in OSCs.^{114,115} For
411 details about charge injection and contact resistance, we recommend the recent reviews by
412 Waldrip et al.,¹¹⁶ Caironi et al.,¹¹⁷ and Noh et al.¹¹⁴

413 The surfaces of organic crystals are prone to contamination and defects and when a metal
414 comes in contact with such a surface, localized states are induced at the interface between the
415 two materials. These states introduce a surface potential which can subsequently increase the
416 injection barrier. Baessler and Vaubel detected surface states in anthracene single crystals by

417 measuring the threshold energies of photoemission of charge carriers from a variety of metals
418 into the crystal.¹¹⁸ They found that high work function metals such as Mg and Pb did not affect
419 the interface, while a surface potential was generated for low work function electrodes such as
420 Ca, Na, Cs and Ba due to electron trapping. A surface trap density of $2 \times 10^{12} \text{ cm}^{-2} \text{ eV}^{-1}$, with a
421 maximum trap depth of $1.3 \pm 0.2 \text{ eV}$ was evaluated. de Boer and Morpurgo investigated this
422 effect by comparing the results of space charge limited current (SCLC) measurements performed
423 on tetracene single crystals in a sandwich structure, with the crystal laminated on a pre-fabricated
424 Au contact (bottom contact), and the top Au contact deposited by electron-beam evaporation.¹¹⁹
425 In spite of the nominally identical electrode/OSC interfaces, they found that the injection was
426 more efficient from the surface of the bottom contact. They concluded that the e-beam
427 evaporation process damages the crystal surface due to interaction with X-rays and high energy
428 electrons during the deposition process, resulting in a larger density of traps compared to the
429 pristine bottom surface. The trap density at the crystal surface was also larger than that in the
430 bulk, highlighting the effect of processing on the surface traps and, consequently, charge
431 transport. This effect was further explored by Coll et al. and they developed a non-destructive
432 deposition method for top contacts, i.e., flip-chip lamination.¹²⁰ The technique was based on
433 nano-transfer printing and involved the adhesion of ultra-smooth patterned contacts onto the
434 organic crystal. This resulted in similar SCLC currents from both top and bottom electrodes
435 confirming that flip-chip lamination preserves the crystal quality.

436

437 **3.3. Environmental effects**

438 Exposure to environment either during device fabrication, handling and/or
439 characterization, often affects the quality of the OSC and can lead to trap formation.
440 Temperature, moisture (H_2O), ambient gases (O_2) and electromagnetic radiation such as light and
441 X-rays are some other possible sources of traps. Recent developments have led to very stable
442 organic electronic devices, a milestone which has been realized through careful device and
443 material design.^{121–124}

444 Traps related to temperature manifest themselves in OFETs as shifts in turn-on voltage
445 V_{on} , subthreshold slope S and threshold voltage V_{th} .^{125,126} The borderline between shallow and
446 deep traps changes with temperature. i.e., at sufficiently high temperatures all traps behave as
447 shallow traps and vice versa. Ambient moisture in pentacene films have been known to cause
448 OFET device degradation, resulting in larger V_{th} , S , and high on-currents.^{127–130} Water molecules
449 can either act as traps for charge carriers or cause redox reactions in the OSC.¹³¹ Using first-
450 principle calculations, it was predicted that water-related defects are energetically favorable in
451 pentacene and hence are more likely to occur.¹³² Such traps have led to bias stress instabilities in
452 OFETs.^{124,133–135} In pentacene single crystal transistors a discrete trap state with density up to
453 10^{12} cm^{-2} was generated during negative bias stress as a result of water adsorbed on the SiO_2
454 dielectric.¹³⁴ Gomes et al. investigated this effect as a function of temperature and discovered
455 that bias-stress effects are only present above 200 K, which corresponds to a known phase
456 transition of supercooled water.¹³⁵ This was observed in several OSCs independent of deposition
457 techniques. Bias stress effects due to water adsorbed by the dielectric can be minimized by
458 rendering the dielectric hydrophobic either by using fluorinated polymers as dielectric,¹³⁶ by the
459 application of SAMs,¹³⁴ by inserting interlayers between the dielectric and OSC,¹³³ or by
460 encapsulating the devices.¹³⁷ Water-related traps in conjugated polymers has recently gained a

461 lot of attention.^{87,124,138} Blom and coworkers, found that hydrated oxygen complexes form
462 electron traps in polymeric electron-only diodes: transport is limited by traps exhibiting a
463 Gaussian distribution centered at ca. 3.6 eV from the vacuum level with a density of $3 \times 10^{23} \text{ m}^{-3}$
464 and a width of $\sim 0.1 \text{ eV}$.¹³⁸ Zuo et al. used a similar approach to show that electron and hole traps
465 created in hole-only and electron-only devices made of several OSCs were a result of water
466 molecules enclosed in nanoscopic voids in the films.⁸⁷ A peak was observed in the slope of the
467 logarithmic current-voltage curve plotted as a function of voltage, which was assigned to a
468 transition from trap-limited to trap-filled charge transport regime. By modeling the curves using
469 a 1-D drift-diffusion model, hole and electron trap distributions were determined to be
470 consistently centered around 0.3-0.4 eV from the HOMO and LUMO levels respectively, for all
471 materials. Solvent-vapor annealing in a saturated *o*-xylene environment removed majority of
472 water in the nanovoids through molecular rearrangements, resulting in suppression of the
473 trapping peak. The study has recently been expanded to include small molecules, proposing a
474 universal design rule to achieve trap-free bipolar transport in organic devices.⁸⁶ Recently,
475 Nikolka et al. investigated bias stress effects in conjugated polymers due to the existence of
476 water molecules in the voids of the polymer films that act as charge carrier traps.¹²⁴ They showed
477 that incorporation of solvent additives or dopants displaces the water molecules and enhances the
478 operational stability of the device.

479 Various types of oxygen-related traps in pentacene have been studied theoretically and
480 experimentally.^{48,132,139,140} Northrup et al. predicted that trap states form when an H-atom is
481 replaced with an O-atom that forms a double bond with the C-atom.¹³⁹ Another possible defect,
482 where an O-atom bridges two C-atoms of neighboring pentacene molecules, was predicted to
483 generate trap states with energies in the range 0.33-0.4 eV above the valence band edge.¹³²

484 Batlogg and coworkers studied the effect of oxygen on the trap DOS spectrum of pentacene thin-
485 film transistors and found that a broad peak centered at 0.28 eV from the valence band edge,
486 with a total volume density $\sim 10^{18} \text{ cm}^{-3}$, was created. A similar peak was observed by Knipp et al.
487 in pentacene films exposed to oxygen under a continuous bias stress.¹⁴⁰ Density functional
488 theory calculations suggested the formation of an oxygen-pentacene complex, which then creates
489 a C-O bond with a neighboring pentacene molecule. The formation of the complex is facilitated
490 by the applied gate-bias under oxygen exposure. Discrete trap states induced upon O_2 exposure
491 have also been observed in rubrene single crystals using temperature-dependent SCLC
492 measurements, where a hole trapping state was resolved at 0.27 eV above the valence band
493 edge.⁴⁸

494 OSCs are inevitably exposed to ionization radiation such as X-rays during structural
495 characterization, or even during operation. Several studies involving intentional exposure of
496 ionizing radiation to elucidate its effect on device metrics and the DOS spectrum have been
497 reported. Exposure of rubrene single crystals to X-rays caused shifts in V_{th} of the OFETs, but
498 surprisingly the mobilities remained unharmed, suggesting that the generated traps are located
499 deep in the bandgap.¹²⁶ Rubrene crystals have also been exposed to He^+ ions and their effect on
500 the trap DOS was studied using temperature-dependent SCLC measurements.¹⁴¹ A discrete peak
501 at 0.35 eV from the HOMO edge was resolved with trap densities ($\sim 10^{16} \text{ cm}^{-3}$) initially
502 increasing with radiation dosage and saturating at higher dosages. The formation of the trap was
503 attributed to C-H bond breaking and hydrogen loss.

504

505 **4. Effect of charge carrier traps on electronic devices**

506 The presence of traps in OSCs has a profound impact the performance of electronic
507 devices. In this section, we briefly discuss such effects in OFETs, OLEDs and OPV devices. In
508 OLEDs, electrons and holes emitted from opposite sides of the OSC recombine radiatively to
509 emit light and traps can cause non-radiative recombination, thus reducing the efficiency of the
510 devices.^{6,142,143} In addition to reducing the charge carrier mobilities, which also results in low
511 efficiency, the presence of traps can cause device degradation.^{144,145} OPVs are based on organic-
512 organic heterojunctions where electron-hole pairs (excitons) are generated from two different
513 OSCs upon absorption of light. The excitons dissociate into free carriers at the heterojunction
514 and are carried out separately to the external circuit. Traps can cause non-radiative Shockley-
515 Read-Hall recombination of the dissociated charge carriers, decreasing the quantum efficiency of
516 the devices.^{146,147} Traps also alter the energy level alignment at the organic-organic
517 heterojunction.¹⁴⁸⁻¹⁵⁰ In addition to impacting the fill factor, the misalignment between the
518 energy levels will directly influence the maximum achievable open-circuit voltage.¹⁴⁹ On the
519 other hand, traps can assist with the dissociation of excitons into free carriers.¹⁵¹ The excitons are
520 bound together by high Coulomb energy which acts as an energy barrier for dissociation. The
521 electrons and holes can dissociate down to lower energy states formed by traps and finally
522 overcome the barrier, thereby increasing the efficiency of the devices.

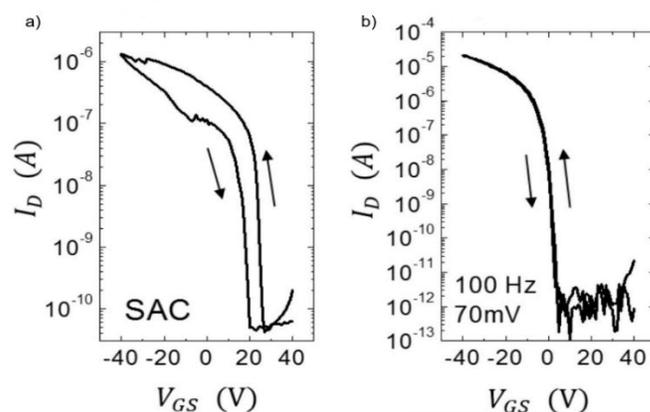
523 OFET technology holds great promise to realizing applications such as active matrix
524 OLEDs, radio frequency identification (RFID) tags, electronic paper and sensor arrays. In
525 addition, they offer a versatile platform for charge transport studies under different charge
526 density regimes and an experimental tool for unambiguous determination of charge carrier
527 mobilities. An important parameter that defines the electrical performance of OFETs is the

528 mobility of the charge carriers in the transistor channel, μ , which represents the average speed at
529 which the carriers move in the presence of an electric field. Trapped charge carriers reduce the
530 effective mobility, with the density of traps and trapping timescale defining the macroscopic
531 transport. In the presence of traps, the mobility is gate-voltage dependent.^{31,152,153} At low gate-
532 source voltages, the injected/accumulated charges occupy the available trap states and the drain
533 current is the result of charge transport occurring through thermally-activated hopping/tunneling
534 between these states. As the gate-voltage increases, the trap states are gradually filled, and at
535 sufficiently large voltages all states are filled and the charge carriers can finally occupy the
536 extended states and subsequently increase the mobilities. The gate-source voltage required to fill
537 trapping states before charge accumulation is possible in the transistor channel is called the
538 threshold voltage and hence a non-zero threshold voltage is indicative of the presence of traps.¹⁵²
539 In fact, the value of the threshold voltage provides direct access to the density of traps, as will be
540 described in section 6.1.2. However, other effects such as contact resistance and the gate-bias
541 dependent charge carrier concentration in the channel, can also contribute to gate-voltage
542 dependent mobilities.^{102,153–156} The presence of traps and contact resistance are competing effects
543 that obscure device characteristics and it is often difficult to distinguish the effect of one from the
544 other. Bittle et al. studied the effect of molecular ordering in regioregular poly(3-hexylthiophene)
545 (RR P3HT) films on OFET characteristics.¹⁵⁶ A reduction in contact resistance and a shift to
546 field-independent mobilities occurred as a result of narrowing of the density of localized states
547 near the band edge in films with increased crystalline order. Traps can also be manifested in the
548 subthreshold region of the transfer characteristics, where the gate-source voltage is below the
549 threshold voltage and the drain current has an exponential dependency on the gate voltage.⁴
550 Thermal de-trapping of charge carriers from shallow traps can contribute to high off currents,

551 resulting in a less steep subthreshold region and a high subthreshold swing, S .¹⁵⁷ Practical
552 applications require very steep subthreshold swing for fast switching of devices with a
553 theoretical limit of 60 meV at room temperature.⁴ Another salient feature in practical OFETs,
554 resulting from the existence of traps, is the bias stress effect, i.e. the change in the threshold
555 voltage or turn-on voltage due to the application of either a continuous or dynamic gate-source
556 voltage. The shift in the threshold voltage over time caused by bias stress is often modeled using
557 a stretched exponential function.¹⁵⁸ The effect is attributed to several mechanisms and charge
558 carrier trapping within the bulk of the semiconductor, in the dielectric or at the
559 semiconductor/dielectric interface are some of them.¹⁵⁹ The presence of water molecules in the
560 semiconductor or the dielectric has also been proven to cause bias stress.^{133,135} Gate-bias stress
561 effect is typically reversible, meaning the trapped charges can be released back into the extended
562 states upon removal of the applied bias. The carrier trapping and release processes depend on
563 several factors such as the materials employed, biasing conditions, device processing and
564 temperature.¹⁶⁰ Illuminating with bandgap radiation reversed bias stress effects caused by hole
565 trapping in polyfluorene thin film transistors.¹⁶¹ Zschieschang et al. showed that applying a
566 drain-source voltage during the bias stress can decrease the shift in threshold voltage by creating
567 a pathway for the trapped charge carriers.¹⁵⁸ Kippelen and coworkers have demonstrated OFETs
568 with remarkable bias stress stability using ultrathin bilayer gate dielectrics comprising of Cytop
569 and Al_2O_3 .^{122,123,162} The best devices yielded threshold voltage shifts below 0.2 V during
570 continuous gate bias stress at $V_{GS} = -10$ V in the saturation regime ($V_{DS} = -10$ V) for 40 hours and
571 in the linear regime ($V_{DS} = -2$ V) for 100 hours.¹²³

572 Hysteresis in the current-voltage characteristics is another clear indication of the
573 existence of traps. Charge carriers trapped in the semiconductor or at the

574 semiconductor/dielectric interface during the forward voltage sweep get released during the
575 reverse voltage sweep and contribute to differential current. Figure 6 shows hysteresis observed
576 in the drain current I_D vs gate-source voltage V_{GS} curves of an OFET based on diF-TES ADT
577 films processed using two different crystallization techniques.⁷⁵ Films grown from solvent-
578 assisted crystallization (SAC) are characterized by severe hysteresis (Figure 6a) compared to
579 those grown from vibration-assisted crystallization (VAC) (Figure 6b), due to the presence of a
580 higher density of traps at the semiconductor/dielectric interface. The vibrations applied during
581 solvent evaporation provided additional energy to the system to crystallize in the global potential
582 energy minimum, with superior crystalline order. Moisture related trap states also contribute to
583 device hysteresis.^{163,164} Noh et al. showed that hysteresis in a pentacene OFET with poly(4-
584 vinylphenol) (PVP) dielectric caused by moisture adsorption in the polar dielectric could be
585 eliminated by thermal annealing the device in vacuum at 120 C.¹⁶⁴ In addition, slow relaxation of
586 the gate dielectric and charge storage in the gate dielectric are also attributed to hysteresis and
587 therefore the effect has been exploited for memory applications which require storage of
588 charge.¹⁶⁵



589
590 *Figure 6. Hysteresis in I_D vs V_{GS} curves for OFETs based on diF-TES ADT films processed from*
591 *a) SAC and b) VAC. Adapted with permission from ref.⁷⁵ Copyright 2013, Wiley-VCH.*

592

593 **5. Impact of traps on charge transport mechanisms**

594 The temperature-dependence of charge carrier mobility provides insights into the
595 mechanism of charge transport in a material. An increase in mobility upon cooling (i.e., $\mu \propto T^{-n}$
596 , $0 < n < 3$) is typically observed in high quality OSC single crystals with low trap densities
597 and was attributed to band-like transport.^{16,106,109,110,166–168} The presence of traps (density and
598 distribution, both energetic and spatial) alter the charge transport mechanism significantly, and
599 therefore the dependence of μ on T . As the trap densities increase, a transition from band-like to
600 thermally-activated hopping regime can occur,^{126,169} where charge carriers assume band-like
601 motion close to room temperature and are immobilized in the shallow trapping states at low
602 temperatures, see for example the black curve in Figure 5a obtained in rubrene single crystal
603 OFETs.¹⁷⁰ The temperature activated transport at low temperatures was modelled by an
604 Arrhenius relation, $\mu \approx e^{-\frac{E_a}{kT}}$, where E_a is the activation energy. The mobilities determined from
605 Hall-effect measurements on the same crystal, however, increased with decreasing temperature
606 in both the high and low temperature regimes (blue curve of Figure 5a).¹⁷⁰ Hall mobilities
607 describe the motion of free charge carriers, since trapped charges do not respond to the Lorentz
608 force. Therefore, Hall measurements are indicative of intrinsic transport, where charge carriers
609 move in delocalized bands in between trapping events. Figure 5b shows μ vs T plots for a
610 solution processed 6,13-bis(triisopropylsilylethynyl) pentacene (TIPS-pentacene) OFET with
611 Cytop dielectric obtained at different drain-source voltages.¹⁷¹ At low drain-voltages, the
612 mobility exhibits an activated behavior over a wide temperature range, with a small activation
613 energy of $E_A = 5.7$ meV: in this regime the transport is dominated by shallow traps. At
614 sufficiently high fields, the traps are filled, and as a result, μ increases with decreasing T . As

615 mentioned in Section 3.2.1, the strain induced at the interface between the semiconductor and

616 dielectric due to the CTE mismatch between consecutive device layers can also introduce traps.

617 The example in Figure 5c shows thermally-activated transport for the case of FETs fabricated at

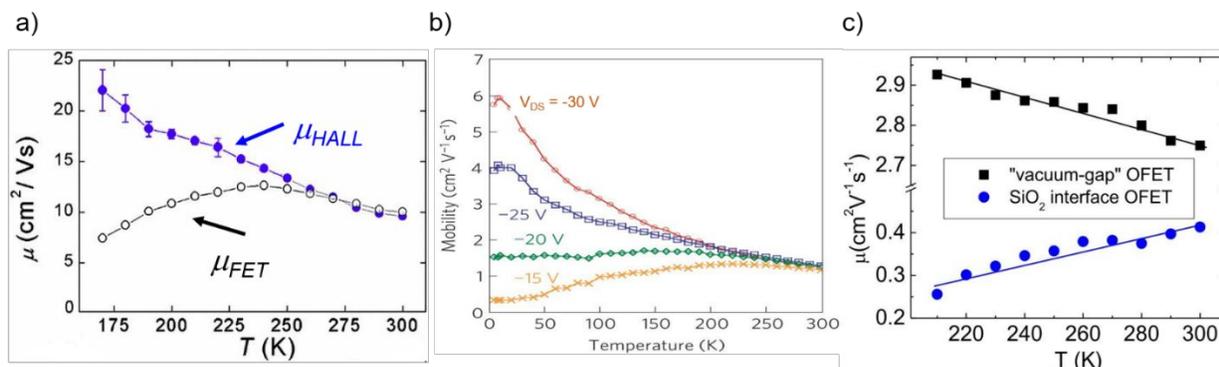


Figure 5. μ vs T plots for a) rubrene single crystals, Adapted with permission from ref,¹⁷⁰

Copyright 2005, American Physical Society, b) TIPS-pentacene thin films at different drain-

source voltages, Adapted with permission from ref,¹⁷¹ Copyright 2010, Springer Nature Ltd, and

c) diF-TEG ADT crystals with SiO_2 dielectric (blue circles) and vacuum dielectric (black

circles). Adapted from ref,¹⁰⁵ Copyright 2017, National Academy of Sciences.

618 the interface between 2,8-difluoro-5,11-bis(triethylgermylethynyl) anthradithiophene (diF-TEG
 619 ADT) ($\text{CTE} = 162 \text{ ppm K}^{-1}$) and SiO_2 dielectric ($\text{CTE} = 4.1 \text{ ppm K}^{-1}$) (blue circles).¹⁰⁵ FETs
 620 fabricated on similar crystals, but with vacuum dielectric, where thermal strain is absent,
 621 exhibited band-like transport (black squares). Investigation of a large number of
 622 semiconductor/dielectric combinations confirmed that the result cannot be explained simply on
 623 the basis of Frölich polarons, and the microstrain plays a critical role. Laudari and Guha
 624 investigated charge transport in TIPS pentacene FETs with ferroelectric polymer dielectrics.¹⁷²
 625 While the reference FETs consisting of non-ferroelectric dielectric (SiO_2) showed activated
 626 transport, a band-like temperature dependence of the mobility was observed within the
 627 ferroelectric temperature window in devices with poly(vinylidene fluoride-trifluoroethylene)
 628 (PVDF-TrFE) dielectric due to de-trapping of charge carriers from shallow traps arising from
 629 changes in the electric polarization of the dielectric. Merlo and Frisbie observed two distinct

630 thermally-activated transport regimes in FETs based on RR P3HT nanofibers due to the presence
631 of a double distribution of traps.¹²⁵ The high activation energy in the high-temperature regime
632 was attributed to the presence of deep donor-like traps, while the low-temperature regime
633 exhibited a low activation energy resulting from acceptor-like shallow traps. A transition
634 between the two regimes was observed, with the transition temperature depending on the gate
635 voltage (195 K for $V_{GS} = -12$ V and 250 K for $V_{GS} = -32$ V). At larger gate voltages, since all
636 deep traps are filled, the distinction between the two regions disappeared and only the effect of
637 shallow traps was manifested in the Arrhenius plot. Nelson et al, observed both a temperature-
638 independent mobility, and an activated charge transport in thin-film pentacene OFETs depending
639 on the quality of the films (i.e. trap densities).¹⁷³ A similar trend was found in solution deposited
640 OSCs, where the activation energy was proportional to the trap densities.¹⁰²

641 **6. Experimental techniques to detect and characterize traps**

642 Determining the origin, concentration and composition of charge carrier traps in OSCs, as
643 well as their spatial and energetic distribution, is not trivial and remains a challenge, in spite of
644 the tremendous efforts dedicated on this topic. Nevertheless, progress has been remarkable and
645 access to the density of trap states spectra has led to significant improvements over the years in
646 device performance and reliability. Several experimental techniques have been developed to
647 access traps, but since each of them includes different levels of approximations, have varying
648 sensitivities, and cover different ranges of energy distributions, the results are not always
649 consistent. This section aims to cover the most popular experimental techniques employed in the
650 detection and characterization of traps. The benefits and limitations of each technique, along
651 with a few examples where they have been adopted will be outlined.

652

653 **6.1. Electrical Measurements**

654 **6.1.1. Space-charge limited current (SCLC) measurements**

655 SCLC measurements are based on the concept of unipolar injection of charge carriers
 656 from an ohmic contact into the bulk of the semiconductor. Here we will discuss this technique in
 657 the context of trap densities and energy spectra. When a high density of charge carriers is
 658 injected from a contact into the semiconductor, a space charge region is formed within the
 659 semiconductor, which subsequently alters the flow of charge carriers. The presence of traps
 660 influences the current flow, hence measurements of the current density, J , as a function of the
 661 applied voltage $J = f(V)$, provide insights into the localized trapping states. The experimental set
 662 up for SCLC measurements is simple and involves sandwiching of a semiconductor in between
 663 two electrodes in a parallel plate geometry. The simplified phenomenological SCLC theory is
 664 based on an idealized model which assumes ohmic contacts and diffusion-free currents from
 665 unipolar charge carriers for a single discrete distribution of shallow traps. The current-voltage
 666 relation is given by,³⁵

$$J_{SCLC} = \frac{9\mu\varepsilon_s\varepsilon_0\theta}{8L^3}V^2 \quad (3)$$

667 where μ is the charge carrier drift mobility, ε_s is the relative permittivity of the semiconductor,
 668 ε_0 , the permittivity of free space, L is the spacing between the electrodes, and θ , the ratio of free
 669 charge carriers (n_{free}) to total charge carriers (n_{total}) defined by:

$$\theta = \frac{n_{free}}{n_{total}} = \frac{N}{N_t} \exp\left(\frac{E_t}{kT}\right) \quad (4)$$

670 Here N_t is the total trap density, N is density of transport sites available for conduction (for
 671 electron only and hole only transport, N is the effective density of states in the conduction band

672 (N_C) and valence band (N_V), respectively), and E_t is the energy of the shallow trap with respect to
673 the band edge. $\theta \leq 1$ and is independent of the applied voltage. When $\theta = 1$, Equation 4 reduces to
674 the Mott-Gurney law for trap-free insulators, referred to as Child's law for solid-state.

675 Figure 6a illustrates a SCLC current-voltage curve for the case of a discrete shallow

676 trapping state. The graph is characterized by the Ohmic region at low voltages, where the current

677 increases linearly with voltage, then the SCLC regime at intermediate bias, followed by the

678 SCLC trap-free regime at high voltages. The current in the latter two regimes follow a quadratic

679 dependency on the applied voltage. The equations governing the current in each region are

680 provided as inset.¹⁷⁴ For a semiconductor with traps, a fraction of the injected charges will not

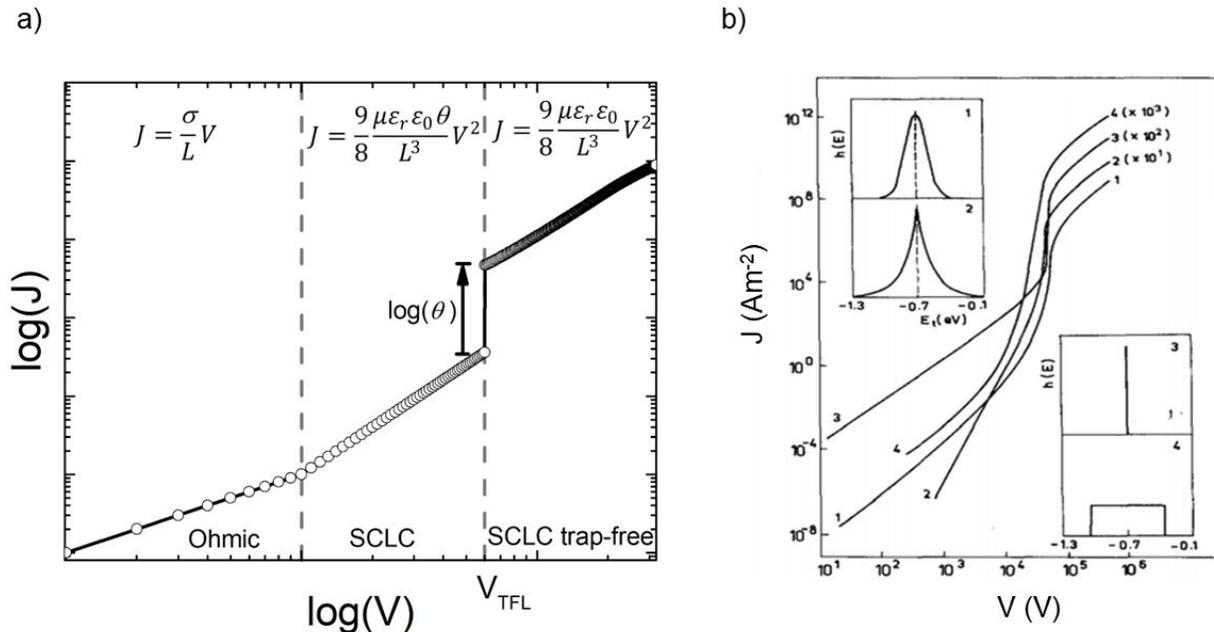


Figure 6. a) Typical current-voltage characteristics from SCLC measurements for a discrete distribution of shallow traps characterized by the Ohmic, SCLC and SCLC trap-free regimes. Inset presents the equations governing J and V in the respective regimes. b) Calculated current-voltage characteristics for various distributions of trapping states as shown in the insets 1. Gaussian distribution, 2. double exponential distribution, 3. discrete distribution and 4. uniform distribution, all centered at 0.7 eV from the valence band edge. Adapted with permission from reference ¹⁸². Copyright 1990, Elsevier Ltd.

681 participate in transport because they are captured by the traps. This results in a reduction in
 682 current by a factor of θ . Assuming one dominant trap state, at higher voltages, an abrupt
 683 transition from the space charge limited regime to the trap filled limit occurs when the quasi-
 684 Fermi level crosses the discrete trap level. This process is evident in the J - V curves as a sudden
 685 increase in the current at a voltage called the trap-filled limit voltage (V_{TFL}) which is used to
 686 estimate N_t (per unit volume per unit energy):

$$N_t = \frac{\epsilon_r \epsilon_0}{eL^2} V_{TFL} \quad (5)$$

687 At voltages higher than V_{TFL} , all traps are filled and the semiconductor is trap-free. The current
 688 after this point follows the Mott-Gurney law for a trap-free insulator. SCLC measurements have
 689 been used to estimate N_t in single crystals such as rubrene ($N_t \sim 10^{15} \text{ cm}^{-3}$),¹⁷⁵ pentacene ($N_t \sim 10^{11}$
 690 cm^{-3}),⁸⁴ tetracene ($N_t \sim 5 \times 10^{13} \text{ cm}^{-3}$),¹⁷⁶ and hydroxycyanobenzene ($N_t \sim 10^{13} \text{ cm}^{-3}$).¹⁷⁷

691 For the case of multiple discrete trap states, the J - V curves exhibits several sharp
 692 increases in the current as the quasi-Fermi level crosses through each trap state. Reaching the
 693 trap-free limit is experimentally difficult, especially when the trap states are broadly distributed
 694 in energy, as it is the case in most OSCs. The oversimplified assumption of a single discrete
 695 distribution of shallow traps may be justified for ultra-pure single crystals, which are known to
 696 have very low density of traps, but it is not accurate for polycrystalline films. Further, the
 697 difficulty in interpreting the experimental J - V curves as they deviate from the $J \propto V^2$ dependency
 698 to other forms such as $J \propto V^n$ with $n > 2$ required that other types of distribution functions
 699 representing a quasi-continuous energy distribution of traps states be considered. A typical
 700 distribution is an exponential distribution of traps of the form:¹⁷⁸

$$N(E_t) = \frac{N_t}{kT_c} \exp\left(-\frac{E_t}{kT_c}\right) \quad (6)$$

701 where T_c is the characteristic temperature of the exponential trap DOS. The J - V relation for such
 702 a distribution follows,^{178,179}

$$J_{SCLC} = Ne\mu \left(\frac{\epsilon_s \epsilon_0}{eN_t \exp\left(\frac{T_c}{T}\right)} \right)^m \left(\frac{m}{m+1} \right)^m \left(\frac{2m+1}{m+1} \right)^{m+1} \frac{V^{m+1}}{L^{2m+1}} \quad (7)$$

703 where $m=T_c/T$ and is related to the width of the distribution. Typically, it is assumed that $T_c > T$,
704 which implies $m>1$. For $T_c<T$, this expression reduces to the case of shallow traps (Equation 3)
705 with $m=1$. Comparing equations 3 and 7, it can be deduced that the SCLC current in a trap-
706 limited semiconductor scales as $N/(N_t)^m$. Therefore, for $m>1$, by simultaneously reducing N and
707 N_t , it is possible to reduce trapping effects by a great extent. Indeed, Blom and coworkers
708 adopted a method called trap dilution through blending the polymers with a high-bandgap
709 semiconductor^{76,180} and eliminated the dominant electron trapping in conjugated polymer blends
710 with 10% active semiconductor and 90% high-bandgap host.¹⁸⁰ This led to the fabrication of
711 OLEDs with balanced electron and hole transport and reduced non-radiative trap-assisted
712 recombination, resulting in a doubling of efficiency at a ten-fold reduction in material costs.

713 While an exponential distribution explains $n>2$ exponent values, with n being a constant,
714 it cannot resolve curves with n monotonously increasing with applied voltage.^{178,181} Other types
715 of energy distributions have also been considered for the analysis of the J - V curves. The
716 Gaussian distribution function proposed by Silinsh is an example.³³ An S-shaped dependence
717 observed in the logarithmic J - V plot at voltages above V_{TFL} was attributed to Gaussian traps and
718 in the case of several such distributions, a step-like J - V characteristics is evident.³³ The analytical
719 expression for J - V relation varies with the applied voltage range as the quasi-Fermi level
720 coincides with different regions of the Gaussian (for example, tail or peak), depending on the
721 voltage applied. Therefore, different analytical expressions have been proposed for different
722 voltage ranges and slopes n .³³ Figure 6b illustrates the J - V curves predicted for several trap
723 distributions such as Gaussian, exponential and uniform. An important outcome of assuming
724 quasi-continuous distributions is that it allows the determination of the trap DOS as a function of
725 energy in the band gap. Such a deduction however requires modelling experimental J - V curves to

726 expressions analytically or numerically derived from theoretical models which requires *a priori*
727 assumptions on the energetic profile of traps. Since experimental curves are often interpreted
728 using integrating techniques involving asymptotic equations, details of the energetic distributions
729 can be lost, leading to incorrect results.¹⁸² Therefore, several efforts focused on developing
730 methods for extraction of trap parameters from the experimental J - V curves for an arbitrary
731 distribution of trap i.e., without making an *a priori* assumption on the energetic distribution.
732 Nespurek and Sworakowski developed the differential method which took the first derivatives of
733 the experimental J - V curves to extract trap parameters.¹⁸³ Later, Schauer et al put forward the
734 thermally modulated SCLC method (TM-SCLC), also called temperature dependent SCLC (TD-
735 SCLC), in which the energy of the trapping state is determined separately from the experimental
736 activation energy, E_a of the conductivity σ , in addition to the differential evaluation of the J - V
737 curves.^{183–185} The J - V curves are measured at different temperatures in order to determine $E_a(V)$
738 from the slope of the Arrhenius plot $\ln \sigma$ Vs $1/T$. TD-SCLC measurements performed on high-
739 purity single crystals of rubrene identified the presence of two exponential trap DOS: one with a
740 steep distribution close to the band edge and another with a shallower distribution in the band
741 gap.⁴⁸ The breadth of the distribution, as well as the trap densities, varied from sample to sample
742 due to the fact that the crystals are sensitive to growth conditions and atmospheric contaminants.
743 The purest sample yielded deep trap densities as low as 10^{15} cm^{-3} , while densities as high as 10^{17}
744 cm^{-3} were measured in other crystals. In addition, traps created by means of a controlled
745 exposure to activated oxygen were detected as a discrete peak in the DOS spectra at 0.27 eV
746 above the mobility edge. More recently, Nikolka et al., characterized water-related traps in the
747 bulk of a polymer films using TD-SCLC.¹⁸⁶ The addition of small molecular species displaced

748 the water-induced traps to yield a narrow density of tail states (in the order of kT) near the band
749 edge akin to that of molecular single crystals.

750 Effects such as diffusion currents, non-homogeneity of the sample, spatial distribution of
751 traps and the existence of an energy barrier at the metal/semiconductor interface are neglected in
752 SCLC theory. This poses difficulties in accurately interpreting the experimental J - V curves and
753 several new models have been proposed to refine SCLC analysis.^{183–185,187–192} The effect of the
754 diffusion component on the current has been introduced by Bonham.^{187,188} Dacuña and Salleo
755 included contact asymmetry and diffusion currents to characterize the trap distribution.¹⁹⁰ They
756 assumed a mobility edge model with a Gaussian distribution of traps centered around 0.2 eV to
757 obtain numerical solutions to the drift-diffusion equation, but the model could only reproduce
758 data within the energy range of 0.1–0.3 eV. Diffusion currents caused by contact asymmetry
759 masked the states shallower than 0.1 eV and deeper than 0.3 eV and a work function offset of
760 0.58 eV for both contacts was necessary to match the experimental data. Khan and Xun later
761 extended this model to include a DOS with an exponential tail in addition to the Gaussian.¹⁹¹
762 Dacuña and Salleo also showed that the assumption of a homogeneous trap distribution is invalid
763 and that an asymmetric distribution of traps exists in the semiconductor.¹⁹³ A spatial distribution
764 of traps near the top contact (with a trap density of $1.2 \times 10^{12} \text{ cm}^{-3}$ and a characteristic width of
765 32.3 nm from the semiconductor/metal interface) was needed to model the experimental curves
766 of a rubrene crystal under both forward and reverse conditions over different temperatures.

767 While SCLC measurements are experimentally easy to perform as they only require two-
768 terminal current-voltage measurements, careful analysis, often involving advanced numerical
769 modelling, is required for the accurate determination of trap parameters. For this reason, OFET
770 measurements take preference in the extraction of trap DOS spectrum. In addition, as the charge

771 carrier density, and hence the quasi-Fermi level, is modulated by the gate voltage independently
772 of the current in the transistor channel, OFET measurements are more versatile in the extraction
773 of trap parameters as will be discussed in the following section.

774 **6.1.2 OFET measurements**

775 In OFETs, the application of gate voltage causes the quasi-Fermi level of the OSC to
776 move towards the band edges, sweeping through any trap states present in this energy interval.
777 Therefore, OFETs provide an excellent tool for probing the density of trap states in OSCs. Here,
778 charge carriers accumulated from the gate voltage move in the vicinity of the
779 semiconductor/dielectric interface and therefore, OFET measurements probe the density of
780 interfacial traps, in contrast to SCLC measurements which accesses traps within the bulk of the
781 semiconductor. The two methods are thus complementary.

782 The simplest methods for extracting information about traps using OFETs involve the
783 threshold voltage V_{th} and subthreshold swing S . Details on the determination of V_{th} , and S and are
784 provided in a recent tutorial focused on OFETs.¹⁰ Since V_{th} is the gate-source voltage required to
785 fill traps at the organic/semiconductor interface before mobile charge carriers are accumulated in
786 the transistor channel, it can be used to estimate the concentration of traps that are filled per unit
787 area, N_{it}^s ,

$$N_{it}^s \approx \frac{C_i V_{th}}{e} \quad (8)$$

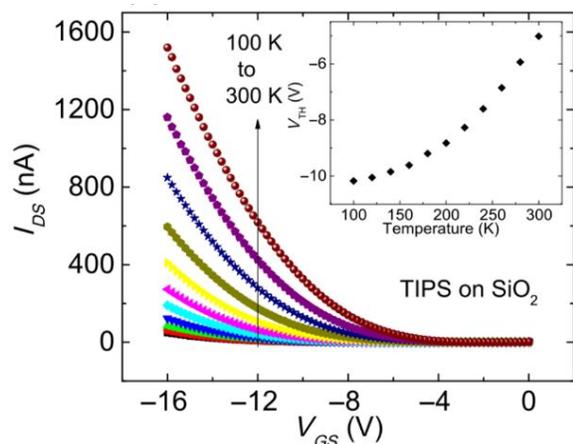


Figure 7. Transfer characteristics of a TIPS pentacene OFET with SiO₂ dielectric measured at different temperatures. Inset shows the threshold voltage as a function of temperature.

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788 where C_i is the areal capacitance of the dielectric and e the elementary charge. As the
 789 temperature decreases, the injected charge carriers have less energy to be thermally activated into
 790 the transport level and hence a larger gate-source voltage is needed to accumulate mobile charges
 791 in the channel, leading to an increase in V_{th} . Figure 7 shows the transfer characteristics of a TIPS
 792 pentacene OFET with SiO₂ dielectric obtained at several different temperatures.¹⁷² The inset
 793 shows an increase in V_{th} as the temperature is reduced. With the decrease of temperature, the
 794 quasi-Fermi level moves further down towards the HOMO level filling up more traps. The
 795 change in V_{th} caused by cooling is therefore a measure of the surface density of traps lying within
 796 a few kT from the band edge.¹²⁶

$$\frac{\partial V_{th}}{\partial T} \approx \frac{e}{C_i} \frac{\partial N_t^s}{\partial T} \quad (9)$$

797 The density of traps per unit area per unit energy, D_t^s is determined from the following:

$$D_t^s = \frac{\partial N_t^s}{\partial E} = \frac{C_i \partial V_{th}}{ek \partial T} \quad (10)$$

798 Here k is Boltzmann's constant.

799 Equation 10 was used to determine the areal trap density close to the HOMO band edge in
800 rubrene single crystals with an air-gap dielectric.¹²⁶ V_{th} increased quasi-linearly upon cooling and
801 a density of $10^{12} \text{ cm}^{-2} \text{ eV}^{-1}$ was evaluated from the slope of the V_{th} vs T plot.

802 Another method to evaluate the trap density is by measuring S . The following expression
803 for the subthreshold swing can be used to estimate the density of interfacial trap states.¹⁹⁴

$$S = \frac{kT \ln(10)}{e} \left(1 + \frac{e \sqrt{\epsilon_s N_{bulk}^v} + e^2 N_{it}^s}{C_i} \right) \quad (11)$$

804 where, N_{bulk}^v is the bulk trap density per unit volume per unit energy, N_{it}^s is the interfacial trap
805 density per unit area per unit energy and ϵ_s is the dielectric constant of the semiconductor. It is
806 hard to separate the contribution of bulk traps and surface traps to the subthreshold swing, but by
807 setting $N_{bulk}^v = 0$ an upper limit for N_{it}^s can be determined and vice versa. Since the subthreshold
808 region is defined by $V_{GS} < V_{th}$, the quasi-Fermi level is located far from the band edges and hence
809 the S method probes deeper band gap states than the V_{th} method. However, the presence of any
810 shallow trap states can result in high off-currents which can impact S and therefore the accurate
811 determination of deep trap densities.¹⁵⁷ Smith et al. used the above two methods to determine the
812 total trap density of small molecule/polymer blended OFETs.¹⁵⁷ Different processing conditions
813 resulted in two distinct film microstructures characterized by small grains (SG) and large grains
814 (LG). Areal trap densities determined using equation 11 yielded values of $1.8 \times 10^{12} \text{ cm}^{-2} \text{ eV}^{-1}$
815 for SG films and $1.4 \times 10^{12} \text{ cm}^{-2} \text{ eV}^{-1}$ for LG films at 110 K. The difference was more
816 significant at 200 K, indicating that a higher density of trapped charges resides in the SG films.

817 A shallow trap density of $\sim 1.5 \times 10^{13} \text{ cm}^{-2} \text{ eV}^{-1}$ was obtained for both films using equation 10.
818 An order of magnitude difference in the trap densities evaluated from V_{th} and S was attributed to
819 the different regions of traps probed by each method.

820 Podzorov and coworkers used photo-induced charge carriers in the channel of a single
821 crystal tetracene OFET with parylene dielectric to extract information about shallow traps.¹⁹⁵
822 Application of a gate bias under illumination (V_{GS}^{illum}) caused charge carriers to move across the
823 dielectric/OSC interface and into the dielectric, resulting in a shift in the turn-on voltage, V_{on} . A
824 monotonic decrease in mobility was observed when electrons were transferred, and no change
825 was detected upon transfer of holes due to the fact that electrons immobilized in the dielectric
826 create potential wells that act as shallow traps while the holes create potential bumps that only
827 scatter them. The density of photo-induced charges was estimated from the shift in V_{on} using
828 $\Delta N = C_i \Delta V_{on} / e$. By measuring the mobility as a function of the photo-induced density of
829 shallow traps, $\mu(N)$, a trap density of $(3 \pm 0.5) \times 10^{11} \text{ cm}^{-2}$ (prior to illumination) and an average
830 trapping lifetime of $50 \pm 10 \text{ ps}$ was evaluated.

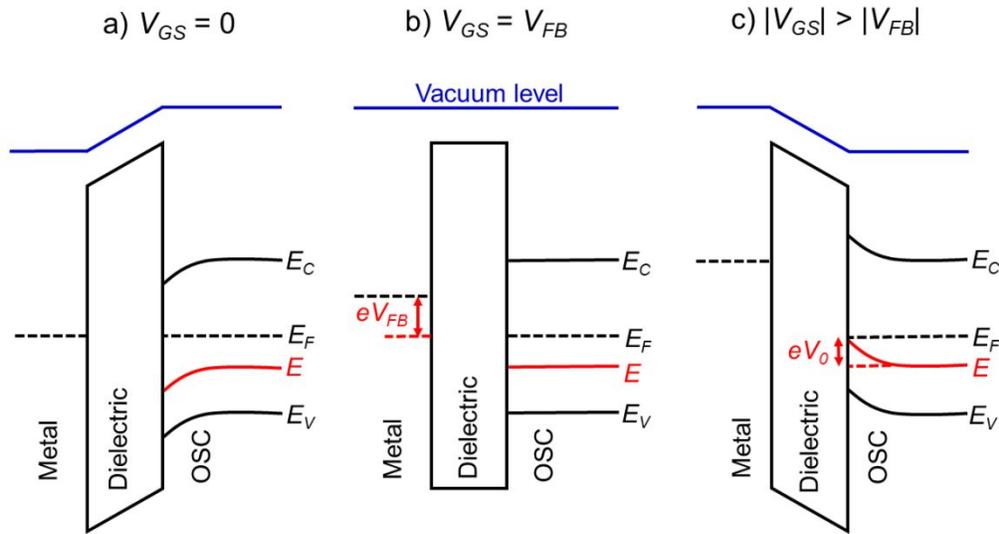
831 The above methods provide a useful comparison of shallow and deep trap densities, but
832 they do not provide details on the energy distribution of the trapping states within the band gap,
833 i.e., the trap DOS function. In order to quantitatively determine the trap DOS, several analytical
834 methods and numerical methods have been developed. In the following, a few methods will be
835 discussed to varying extents. Determination of the trap DOS spectrum exploits the fact that the
836 gate bias induces band bending at the interface between the semiconductor and the dielectric.
837 Figure 8 depicts the energy diagram for gate/dielectric/semiconductor interface in three voltage
838 regimes. A p-channel transistor is considered here and the extension to n-channel transistors can
839 be obtained by changing the sign of the gate voltage and considering states in the upper half of

840 the band gap. An initial band bending occurs even under zero bias due to energy level mismatch
 841 between the adjacent layers (Figure 8a). In order to achieve flat bands, a gate-source voltage
 842 called the flat band voltage (V_{FB}) is necessary (Figure 8b). Increasing the voltage beyond V_{FB}
 843 causes band bending, as illustrated in Figure 8c, and an arbitrary trap state with energy E
 844 (represented by red solid lines) is now elevated at the interface to coincide with the quasi-Fermi
 845 level. E corresponds to the shift in the energy bands relative to the quasi-Fermi-level at the
 846 interface ($x=0$), i.e., $E=E_V-E_F-eV_0$, where E_V and E_F are the energy of the valence band edge and
 847 the Fermi energy respectively, and $V(x=0) = V_0$ is the interface potential. The dependence of V_0
 848 on V_{GS} , i.e. the function $V_0(V_{GS})$, is the key to obtaining the DOS spectrum and several models
 849 have been developed to extract DOS from this function. The method by Grunewald et al.,
 850 developed for a-Si transistors and later adopted for OFETs by Kalb et al.,^{196,197} is based on the
 851 gate voltage dependence of the field-effect conductivity. The model assumes that the
 852 semiconductor layer is homogeneous and accounts for the initial band bending by calculating the
 853 gate-source voltage above the flat band voltage, i.e., $U_{GS} = |V_{GS} - V_{FB}|$.¹⁹⁶ V_{FB} is assumed to be
 854 the turn-on voltage estimated from the transfer curve. The function $V_0(V_{GS})$ is then obtained by
 855 numerically solving the following equation (See ref ¹⁹⁶ for a complete derivation):

$$\exp\left(\frac{eV_0}{kT}\right) - \frac{eV_0}{kT} - 1 = \frac{e}{kT} \frac{\varepsilon_i d}{\varepsilon_S l \sigma_0} [U_{GS} \sigma(U_{GS}) - \int_0^{U_{GS}} \sigma(\tilde{U}_{GS}) d\tilde{U}_{GS}] \quad (12)$$

856 where ε_i and l are the relative permittivity and the thickness of the dielectric, respectively, $\sigma(U_{GS})$
 857 is the field-effect conductivity evaluated from the linear regime transfer characteristics (I_D vs V_{GS}
 858 curve) using equation 13 and σ_0 is the conductivity at flat band.

$$\sigma(U_{GS}) = \frac{L I_D}{W V_{DS}} \quad (13)$$



859 Here W and L are the channel width and length of the transistor respectively. Then $V_0(V_{GS})$ is
 860 used to determine the total hole density from,

Figure 8. Energy level diagram at the gate/dielectric/semiconductor interface of an OFET at different gate bias, a) at $V_{GS} = 0$ showing initial band bending at the dielectric/semiconductor interface, b) at $V_{GS} = V_{FB}$ illustrating flat bands and c) at $|V_{GS}| > |V_{FB}|$ depicting gate-induced band bending. Solid red lines represent an arbitrary trap state for holes, solid black lines the band edges and the broken black lines the fermi level of the respective material.

861

$$p(V_0) = \frac{\epsilon_0 \epsilon_t^2}{\epsilon_s l^2 e} U_{GS} \left(\frac{dV_0}{dU_{GS}} \right)^{-1} \quad (14)$$

862 The hole density is the convolution of the DOS with the Fermi function and hence a
 863 deconvolution of the hole density is required in order to evaluate the DOS function. For
 864 slowly varying trap densities, the zero-temperature approximation for the Fermi function

865 can be made. The trap DOS is then obtained by numerically differentiating the total hole
866 density with respect to V_0 . i.e.,

$$N(E) \approx \frac{1}{e} \frac{dp(V_0)}{dV_0} \quad (15)$$

867 Therefore, the trap density (per unit volume per unit energy) is plotted as a function of the
868 interface potential which corresponds to the energy of the trap state relative to the quasi-Fermi
869 level.

870 Grünewald's method has been widely explored by the scientific community to determine
871 the trap DOS spectrum. Diemer et al. compared the trap DOS at two different
872 semiconductor/dielectric interfaces, namely the interface of diF-TES ADT thin films with the
873 fluorinated polymer dielectric Cytop and the SiO₂ dielectric.⁹⁷ Devices with Cytop dielectric
874 yielded two orders of magnitude lower trap densities (see Figure 9a), which resulted in an order
875 of magnitude higher charge carrier mobilities compared to the devices with SiO₂ dielectric (an
876 average of $0.17 \pm 0.19 \text{ cm}^2 \text{ V}^{-1} \text{ s}^{-1}$ and $1.5 \pm 0.70 \text{ cm}^2 \text{ V}^{-1} \text{ s}^{-1}$ for SiO₂ and Cytop, respectively).
877 Paterson et al. investigated the impact of charge carrier trapping at the semiconductor/dielectric
878 interface on contact resistance by comparing small-molecule/polymer-blend OFETs with two
879 polymer dielectrics, Cytop and AF2400.⁹⁸ The trap DOS spectrum, evaluated as a function of
880 energy from the quasi Fermi level, indicated similar trap densities deep in the band gap, but
881 increasing much more rapidly for devices with AF2400 as the energy approached the band edge.
882 Devices with AF2400 yielded lower total trap densities and lower contact resistance. In the same
883 study, the DOS analysis was performed on bias-stressed devices and was found that no
884 trapping/detrapping occurs during operation of AF2400 devices. Grünewald's method has also

885 been employed to investigate the effect of p-doping an OSC blend containing the small molecule
886 2,7-Dioctyl [1]benzothieno[3,2-b][1]benzothiophene (C8-BTBT) and the co-polymer IDT-BT
887 (see Figure 9b).¹⁹⁸ A shift in trap DOS was observed only for dopant concentrations higher than
888 1% mol, with pinning of the quasi-Fermi level dominating at lower dopant concentration.

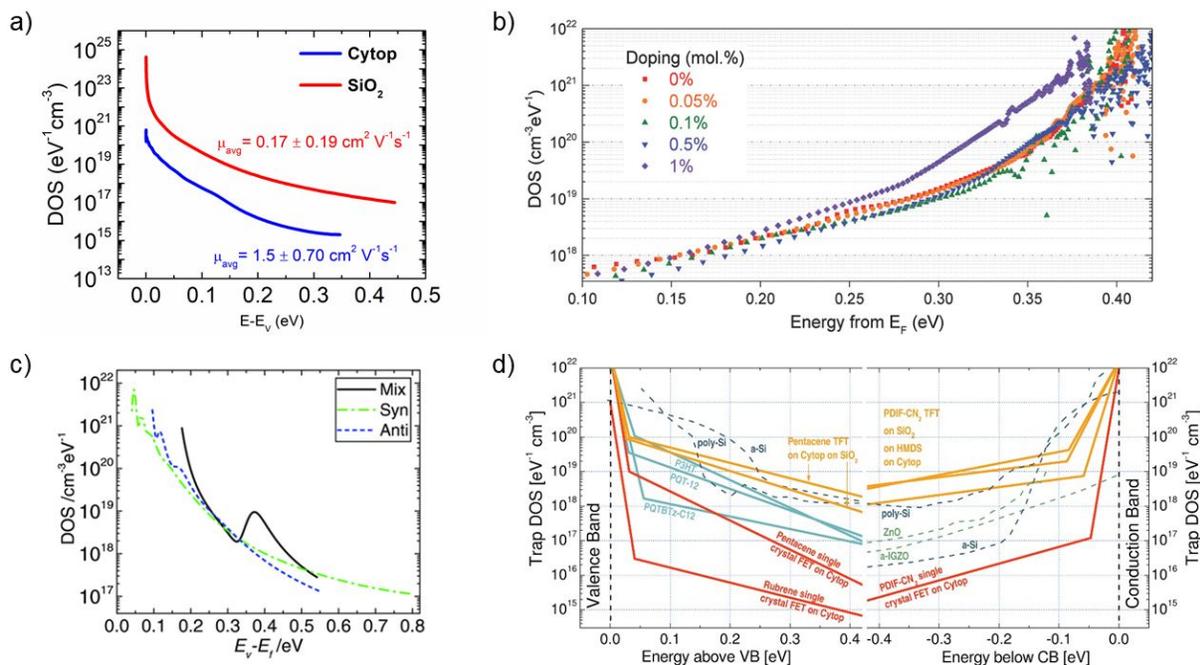


Figure 2 Figure 9. a) Comparison of the interfacial trap DOS spectrum for diF-TES ADT films with Cytop (blue) and SiO₂ (red) dielectrics evaluated using Grünwald's model. The value of mobility is listed in the inset. Adapted with permission from ref,⁹⁷ Copyright 2015, AIP Publishing LLC. b) Effect of p-doping on the trap DOS of OSC/polymer blend OFETs evaluated using Grünwald's model. Reproduced with permission from ref,¹⁹⁸ Copyright 2017, Wiley-VCH. c) Effect of isomer purity of diF-TES ADT on the trap DOS spectrum determined using Method II by Kalb et al. Broken green and blue curves represent trap DOS of pure syn- and anti- isomers respectively while the solid black lines represent that of the mix sample for reference. Reproduced with permission from ref,²⁰⁵ Copyright 2017, Wiley-VCH. d) Comparison of the interfacial trap DOS for several organic and inorganic FETs calculated using the numerical method by Oberhoff et al. Reproduced with permission from ref,²⁰⁸ Copyright 2010, American Physical Society.

890 Grunewald's method considers only the potential drop at the dielectric layer caused by
891 the gate-source voltage and does not account for the potential drop across the interface. i.e., V_{GS}
892 $-V_{FB} = V_{dielectric}$. Such an assumption is justified for devices with thick dielectrics operating at
893 high voltages. In the case of devices operating at low-voltage and with thin dielectrics, however,
894 the potential drop across the semiconductor can be comparable to that across the dielectric and
895 hence cannot be ignored. Recently Geiger et al. addressed this issue and extended the
896 Grunewald's method for low-voltage devices by accounting for the potential drop at the
897 interface, i.e., $V_{GS} - V_{FB} = V_{dielectric} + V_0$.¹⁹⁹ The model was used to calculate the DOS spectrum
898 of two different thin film transistors consisting of a thick and a thin gate dielectric. Devices with
899 thick dielectric yielded similar results using both the original and extended methods. However, a
900 significant difference in trap DOS was observed for devices with thin dielectric, with the newly
901 proposed method being more accurate.

902 Several other analytical methods such as those by Horowitz et al.,²⁰⁰ Lang et al.,²⁰¹
903 Fortunato et al.,²⁰² and Kalb et al.,^{203,204} exist to extract the trap DOS spectrum. These methods
904 are based on the temperature dependence of the field-effect conductivity and therefore require
905 temperature dependent measurements. These methods rely on the concept of the quasi-Fermi
906 level shift induced by a change in the gate-source voltage that, in turn, corresponds to a shift in
907 the activation energy of the conductivity. The activation energy E_a of the field-effect
908 conductivity is evaluated as a function of gate-source voltage, i.e., $E_a(V_{GS})$, in order to determine
909 the energy E of the trapping state ($E \approx E_a = E_V - E_F - eV_0$). The field-effect conductivity is related
910 to the temperature by an Arrhenius relation and therefore by measuring the transfer
911 characteristics at different temperatures, the activation energy at each gate-source voltage can be
912 determined with a linear regression analysis of $\ln \sigma$ vs $1/T$. Several approximations differentiate

913 the methods. For example, Lang et al. consider the charge accumulation thickness ' a ' to be
914 independent of the gate-source voltage,²⁰¹ while Horowitz et al. include the gate voltage
915 dependency in their calculations.²⁰⁰ Fortunato et al. calculate the activation energy of the first
916 derivative of the normalized field-effect conductivity.²⁰² Kalb et al. proposed two methods with
917 method II an extension of method I, which follows equations 14 and 15, but with the interface
918 potential evaluated from the activation energy of the conductivity. Method II by Kalb et al. was
919 formulated following Fortunato et al., who considered a normalized field-effect conductivity in
920 order to account for the temperature dependence of the band mobility μ_0 .^{202,204} This method
921 revealed a discrete trapping state in the band gap of in diF-TES ADT originating from the co-
922 existence of *anti* and *syn* isomers, as illustrated in Figure 9c.²⁰⁵ Ha et al. calculated the trap DOS
923 spectrum for both holes and electrons in an ambipolar transistor based on diketopyrrolopyrrole-
924 benzothiadiazole (PDPP-TBT) copolymer using the method by Lang et al. and method II by
925 Kalb et al.²⁰⁶ Both methods yielded similar results with symmetric trap distributions for both
926 holes and electrons.

927 The analytic methods discussed so far approximate the Fermi-function to that at zero
928 temperature and neglect the temperature dependence of the Fermi energy E_F and interface
929 potential V_0 . The numerical method developed by Oberhoff et al. incorporates Fermi-Dirac
930 statistics into the calculations for the determination of the trap DOS function.²⁰⁷ In this method, a
931 computer program simulates the linear regime transfer characteristics at any temperature for a
932 given distribution of traps and band mobility μ_0 . The parameters describing the DOS are varied
933 until the generated transfer characteristics are a good fit to the experimentally measured curves.
934 A constant DOS at the band edges, with exponential tail states decaying into the band gap, is
935 assumed. The program allows the introduction of an additional Gaussian distribution to account

936 for any discrete trap states. Figure 9d compares the trap DOS spectrum of several p-channel and
937 n-channel OFETs, as well as some inorganic FETs, calculated using the numerical model by
938 Oberhoff et al.²⁰⁸ This plot reveals similar trap DOS in OSCs and inorganic semiconductor thin
939 films despite significant differences in charge carrier mobility. Single crystal FETs occupy the
940 lowest part of the graph, with trap densities several orders of magnitude lower than their thin
941 film counterparts. This highlights the effect of both disorder and morphology on the trap DOS
942 spectrum. In a recent study, Anand et al. found that for devices with similar film morphologies,
943 the nature of the dielectric is the main factor that determines the overall trap densities.¹⁰²

944 Figure 10 compares the trap DOS spectrum calculated using all the methods described in
945 this section applied for the same device, a pentacene thin-film transistor.²⁰⁴ It is clear that both
946 the choice of the method and the parameters assumed *a priori* impact the final results.²⁰⁴ The
947 trap density estimated from the subthreshold swing using Equation 9 is independent of energy
948 and provides only a rough estimate for traps in the vicinity of the quasi-Fermi level located in the
949 mid gap (~ 0.5 eV from E_V). To be noted that the curve obtained from the simulation program
950 accounts for complete Fermi-Dirac statistics and therefore the accuracy of all other curves are
951 evaluated with respect to this. The method by Lang et al. underestimates the trap densities, as
952 evident from the slope of the curve near the band edge, which was attributed to the fact that the
953 dependence of the accumulation layer thickness on the gate-voltage was neglected. Method II by
954 Kalb et al. and Fortunato et al. have better agreement with the results from simulation as they
955 allow for the temperature dependence of band mobility.

956 Takeya and coworkers developed a new technique to extract the trap DOS spectrum by
957 employing McWhorter's model for the measured flicker noise ($1/f$ noise).²⁰⁹ The noise arising
958 from current fluctuations hamper OFET stability and can originate from different sources, with

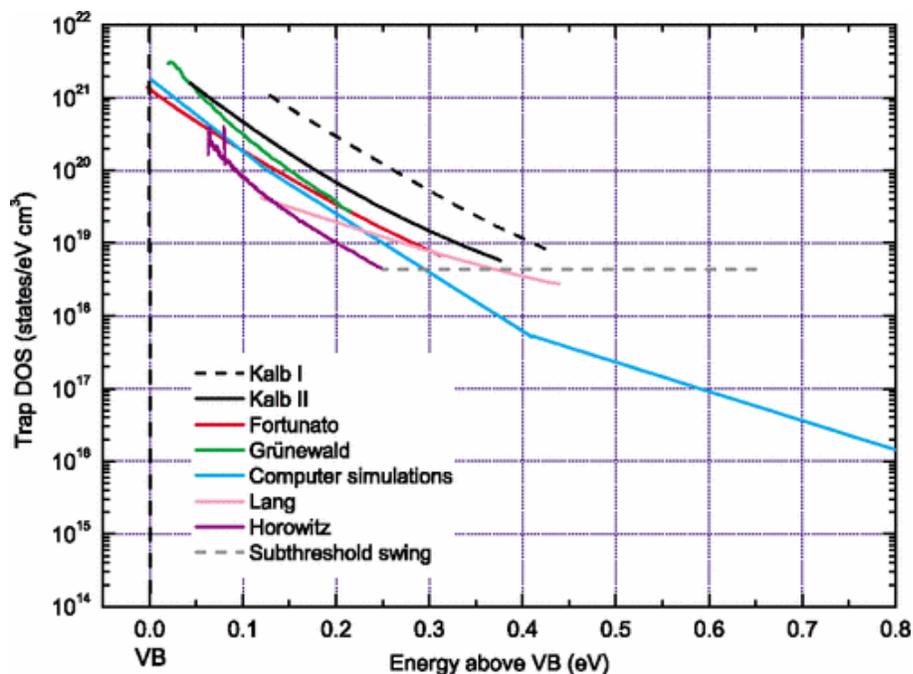


Figure 10. A comparison of the interfacial trap DOS obtained for pentacene thin-film transistors using several analytical and numerical methods. Adapted with permission from ref.²⁰⁴ Copyright 2010, American Physical Society.

959 contact effects and charge carrier trapping being the most common.⁵⁸ In this study, the authors
 960 assumed that charge trapping is the main noise source and evaluated the trap DOS spectrum from
 961 the spectral density in the current noise. The results agree well with those from the numerical
 962 model by Oberhoff discussed earlier. By drastically reducing the structural disorder, they
 963 obtained charge carrier mobilities as high as $15 \text{ cm}^2 \text{ V}^{-1} \text{ s}^{-1}$, band-like transport and record low
 964 flicker noise.

965

966 6.1.3. Impedance Spectroscopy

967 Impedance spectroscopy (IS) involves the measurement of the electrical response of a
 968 material as a function of frequency upon applying an AC voltage. The AC voltage oscillates the

969 quasi-Fermi level of the material and when this coincides with the localized band gap states, the
970 electrical response is altered as a result of trapping/detrapping of charge carriers in these states.
971 Exploiting this phenomenon can provide insights into trapping mechanisms. Analysis and
972 interpretation of the response, however, is not straightforward and several approaches such as
973 capacitance - voltage ($C-V$) analysis,^{210,211} equivalent circuit modelling of the impedance
974 spectrum,^{212,213} and capacitance - frequency ($C-f$) analysis,^{214,215} are employed for this purpose.
975 Each approach comes with several assumptions, requirements and drawbacks, limiting its
976 general applicability. It is beyond the scope of this review to go into an in-depth discussion on
977 the above factors, but the reader is directed to a recent exhaustive review by von Hauff on the
978 subject.²¹⁶ This section will provide a brief comparison between the methods, with emphasis on
979 trap evaluation, along with a few examples.

980 $C-V$ measurements at different frequencies provide estimates for the trap densities, but
981 cannot determine the energy distributions, for which equivalent circuit and $C-f$ modelling is
982 needed. Equivalent circuit modelling has been employed to determine trap distributions in
983 organic metal-insulator-semiconductor (MIS) capacitors based on (P3HT) and various polymer-
984 based gate insulators.^{212,213} Although it is a simple technique that allows for fast analysis of the
985 impedance spectra, the challenge lies in determining an appropriate model that correlates with
986 the frequency response of real devices. $C-f$ eliminates the above problem and hence is more often
987 used to characterize traps. During $C-f$ modelling, the frequency of the applied voltage is swept
988 until a characteristic frequency at which charges are thermally excited out of trap states is
989 recorded. This frequency is used to determine the trapping timescale (i.e. $\omega=2\pi f$). Walter et al.
990 proposed a model for Cu In (Ga)₂ Se solar cells, which was later adopted for OPVs, in order to
991 extract the trap distribution using the following equation:²¹⁷

$$N(E_\omega) = -\frac{V_{FB}\omega}{de kT} \frac{\partial C(\omega)}{\partial \omega} \quad (16)$$

992 where E_ω is the energy of the trap state w.r.t the band edge, $C(\omega)$ is the frequency-dependent
993 capacitance, d is the thickness of the OSC. In a bulk-heterojunction OPV based on a blend of
994 P3HT and [6,6]-phenyl-C61 butyric acid methyl ester (PCBM), a Gaussian-like distribution of
995 traps was determined using this method.²¹⁵ C - f modelling assumes that changes in the
996 capacitance results only from trapping/detrapping of charge carriers. Nevertheless, other
997 contributions to the capacitance are possible and can give rise to artifacts in the trap spectrum.
998 For example, due to the low charge carrier mobility, hence large transit times, the charge carriers
999 can freeze-out at high frequencies as they no longer respond to the modulation of the applied
1000 voltage. Therefore, the artifact, in the guise of shallow trap states, is a result of the contribution
1001 from the geometric capacitance at high frequencies. Numerical simulations indicated that trap
1002 distributions can be reliably extracted for thicknesses of ~ 100 nm and mobilities exceeding 10^{-4}
1003 $\text{cm}^2 \text{V}^{-1} \text{s}^{-1}$.²¹⁴ This was further confirmed by Kirchartz and coworkers when they showed for an
1004 OLED based on P3HT that shallow traps manifested in the trap spectrum were the result of
1005 dielectric relaxation occurring in low mobility OSC with low trap densities.²¹⁸ On the other hand,
1006 deep states with high density of states were accurately determined. C - f analysis can also
1007 determine the energetic distribution of traps when combined with other measurements. For
1008 example, temperature dependent measurements allow the determination of the activation energy
1009 of the trap states.^{219,220} C - f analysis has also been used in conjunction with small signal SCLC
1010 theory, initially developed by Dascalu,^{221,222} to extract trap DOS spectrum. Naito and coworkers
1011 exploited this approach to determine the lifetime and energy distribution of traps in several OSCs
1012 in an OLED configuration.^{220,223,224} Shallow trap distributions were determined using electron-
1013 only and hole only OLEDs, respectively, based on a polyfluorene-based light-emitting

1014 polymer.²²⁰ Higher temperature measurements yielded distributions of deep states as well.
1015 Further modification to this method was proposed to improve the energy resolution of the
1016 measurements by reforming the analytical expression that relate the impedance spectra to the
1017 trap distribution.²²⁴

1018

1019 **6.2. Optical and Thermal Methods**

1020 Optical and thermal methods are based on the photo-induced (radiative) and thermally
1021 induced (non-radiative) transitions among electronic states, respectively. The presence of charge
1022 carrier trapping states in the band gap will inevitably impact such measurements, and this can be
1023 exploited in determining the nature and energetic distribution of traps.

1024 One optical method is photoemission spectroscopy (PES), also known as photoelectron
1025 spectroscopy (PS), which is based on the principle of photoelectric effect. The energy of the
1026 emitted electrons is measured in order to determine their binding energy. The ionization energy
1027 needed for photoelectric effect is provided by various sources such as X-ray (XPS) or UV (UPS)
1028 photons. This method has been used to observe directly the band gap states of single crystals of
1029 rubrene and C₆₀.^{225,226} UPS measurements have been employed to detect Au-induced¹¹² and
1030 disorder/defect-induced²²⁷ band gap states in thin polycrystalline films of pentacene. In C₆₀, a
1031 higher density of states was detected near the valence band edge (10^{19} - 10^{21} eV⁻¹ cm⁻³) which
1032 originated from exposure to atmospheric gases with a negligible contribution from structural
1033 defects such as grain boundaries.²²⁵

1034 Light absorbed by the semiconductor excites the charge carriers residing in the trap states
1035 into the conduction states, thereby generating free charge carriers and subsequently increasing

1036 the electrical conductivity of the sample, a phenomenon called photoconductivity. Thus by
1037 measuring the changes in the current caused by changes in the conductivity, information on the
1038 distribution of traps can be obtained. This method has been used for example, to extract the
1039 interfacial trap DOS spectrum in thin film pentacene-based transistors.²²⁸

1040 Charge modulation spectroscopy, which probes changes in the optical absorption of the
1041 OSC caused by the loss/acquisition of electrons from molecular orbitals, is another powerful
1042 spectroscopic technique that has been used in characterizing traps. When combined with
1043 temperature-dependent electrical measurements, such as FET or two-point measurements in a
1044 diode configuration, CMS can provide insights into trapping mechanisms.^{47,171} The applied
1045 voltage modulates the charge carrier concentration during which shallow trap states are filled and
1046 emptied, subsequently causing changes in the absorption (CMS) spectrum. Sakanoue et al.
1047 observed a sharpening of the absorption peak in the CMS spectra of TIPS-pentacene OFETs at
1048 low temperature (150-200 K) and correlated it to the temperature dependence of mobility.¹⁷¹ The
1049 sharpening was observed in the temperature regime where mobility was thermally activated and
1050 hence was attributed to shallow traps. The absorption peak broadened as the lateral electric field
1051 (drain-source voltage) was increased, implying that charges residing in shallow trap states can be
1052 de-trapped into mobile states by application of the drain-source voltage. Charge modulation
1053 spectroscopy has also been used to observe dynamic disorder induced tail states in various
1054 solution-processed small molecules.⁴⁷

1055 Optical methods are useful to characterize shallow traps, but cannot resolve deep non-
1056 radiative traps, where methods that also require thermal excitations are adopted. One such
1057 technique is the thermally-stimulated current (TSC) measurement, which involves the filling of
1058 band gap states using charges from injection or light absorption followed by thermal excitation

1059 of the trapped charges. The filling of traps is typically done at low temperature (~ 70 K) to ensure
1060 they are not released immediately.³² The sample is then gradually heated until the trapped
1061 charges gain enough thermal energy to get excited out of the trap states, subsequently increasing
1062 the current. The current is recorded as function of temperature to obtain trap density and depth.
1063 The resolution of this technique depends on the rate of sample heating. Trapping states with
1064 depths of 0.03-0.06 eV and 0.13-0.18 eV have been identified using the TSC spectra of OLEDs
1065 based on the polymer poly(p-phenylenevinylene) (PPV).²²⁹ The shallow trap was eliminated by
1066 replacing the ITO electrode with Au, depicting that the reaction of ITO with products eliminated
1067 during conversion of the PPV precursor (such as HCl) lead to the formation of the trap. The deep
1068 trap, on the other hand, appeared regardless of the electrode material and was attributed to
1069 interaction with the environment. Tsang et al investigated the effect of introducing interlayers
1070 of 8-hydroxyquinolino lithium between the hole blocking and electron transporting layers in
1071 OLEDs based on a green emitter (4s,6s)-2,4,5,6-tetra(9H-carbazol-9-yl) isophthalonitrile
1072 (4CzIPN).²³⁰ The measurements indicated the reduction in the deep charge carrier trap density
1073 upon insertion of the interlayer that subsequently enhanced the operational stability of the
1074 devices.

1075 Deep level transient spectroscopy (DLTS) is another useful technique for the
1076 characterization of traps. The standard technique, originally developed for inorganic materials, is
1077 based on measuring the transient capacitance of a device during a thermal scan as a function of
1078 time upon applying a voltage pulse.²³¹ When the voltage pulse is turned on, the quasi-Fermi level
1079 moves in the band gap filling up trap states as it crosses them and when turned-off, the trapped
1080 charges are thermally excited into the bands. Hence, variations in the transient capacitance due
1081 to the discharge of excited charge carriers provide information on trap parameters. However,

1082 since OSCs generally have longer relaxation times compared to conventional semiconductors,
1083 only small variations in capacitance are evident, making it challenging to accurately extract trap
1084 parameters. A modified DLTS technique based on the measurement of charges released from
1085 trapping centers instead of variations in capacitance, hence called charge-based DLTS (Q-
1086 DLTS), yielded better accuracy.²³² In addition, this technique distinguishes between majority and
1087 minority carrier traps. This method has been used to obtain the density, depth and capture cross
1088 section in OLEDs based on PPV,^{232,233} its derivatives,²³⁴ and 4, 4'-bis(4-dimethylaminostryryl)
1089 (DMASB).²³³ Electronic trap distributions in OPV materials PCBM, P3HT and blends of
1090 PCBM/P3HT have been obtained using this method.²³⁵ Trap activation energies of 87 meV and
1091 21 meV were evaluated for pure P3HT and PCBM, respectively. The blends yielded activation
1092 energies ranging from 30-160 meV due to differences in the rate of emission of charge carriers
1093 from the trap states.

1094 Photothermal deflection spectroscopy (PDS) is based on the photothermal deflection of a
1095 laser beam while measuring changes in the thermal properties of a material upon absorption of
1096 light. In this technique, the sample is immersed in a fluid of refractive index that is sensitive to
1097 changes in temperature. A monochromatic beam of light is shone on the sample to excite the
1098 charge carriers into the gap states. The excited charges then decay non-radiatively, emitting heat
1099 in the process, which subsequently changes the temperature of the liquid immersed in. A probe
1100 laser beam grazing the surface of the substrate deflects upon detecting this photo-thermally
1101 induced change. The measurement is repeated at each wavelength of the incident beam.²³⁶ PDS
1102 spans from near-IR to the UV spectral range (~0.1- 4 eV).³² Higher sensitivities can be achieved
1103 by increasing the light exposure time at each wavelength, but this can result in long measurement
1104 times.³² Figure 11a show the PDS spectra obtained for rubrene single crystals.³² The trap DOS

1105 was characterized using three exponential functions (indicated as offset broken lines) with a
1106 steep slope of ~ 36 meV close to band edge and increasing to ~ 61 meV at intermediate energies
1107 and finally to ~ 170 meV deep in the band gap. In addition, a broadening of the DOS was
1108 observed for X-ray irradiated crystals (open circles) in comparison to the pristine crystals (open
1109 squares). The high sensitivity of this method lead to detection of molecular vibrational modes in
1110 the PDS spectrum, as indicated by arrows in Figure 11a. However, this can be problematic as the
1111 absorption from vibrations could mask the features obtained from electronic transitions.³² PDS
1112 has also been used to probe band gap tail states in conjugated polymers resulting from energetic
1113 disorder.^{79,186} Besides, the width of the density of the tail states have been estimated in terms of
1114 the Urbach energy. Urbach energy of several high-mobility conjugated polymers with varying
1115 crystallinity has been determined and correlated with the extent of energetic disorder.⁷⁹ Figure
1116 11b shows the PDS spectra for four polymers, namely IDT-BT (black), poly(2,5-bis(3-
1117 alkylthiophen-2-yl)thieno(3,2-b)thiophene) PBTTT (red) and diketopyrrolopyrrole (DPP) based
1118 polymers, DPPTTT (green), PSeDPPBT (blue).⁷⁹ Exponential tail fits (solid lines) are included
1119 to determine Urbach energies, which are indicated in the inset. IDT-BT yielded the sharpest
1120 absorption onset translating into the lowest Urbach energy of 24 meV, a value which is less than
1121 kT at room temperature, in agreement with its excellent performance in OFETs.⁷⁸

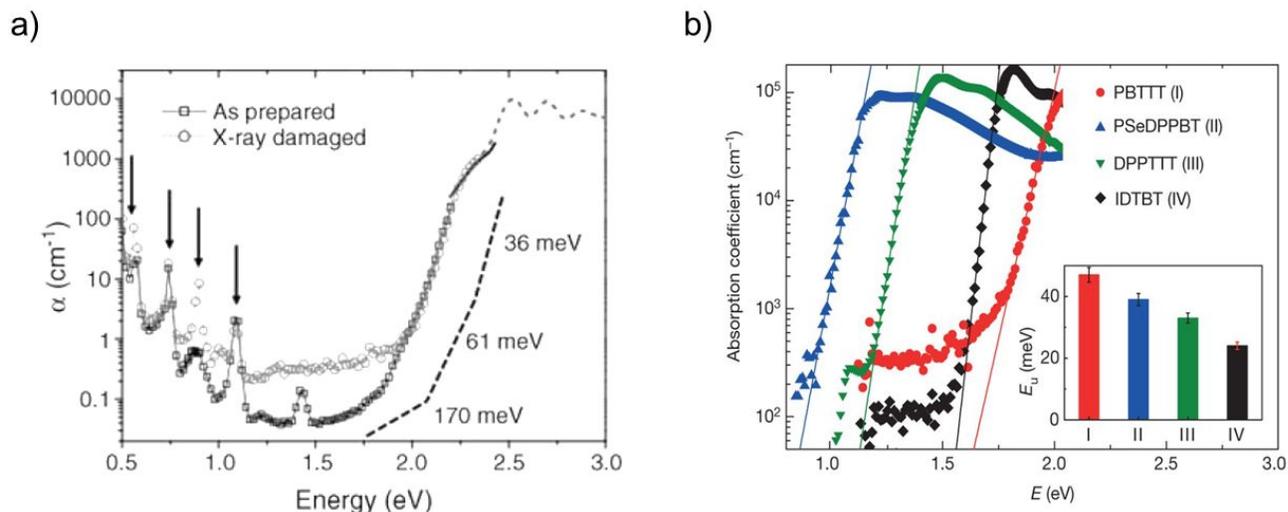


Figure 11. a) PDS spectrum of as-prepared (open squares) and X-ray exposed (open circles) rubrene single crystal. Broken lines represent exponential fits for different spectral regions and are offset for clarity. Arrows represent absorption peaks resulting from molecular vibrations. Reproduced with permission from ref³². Copyright 2013 Wiley-VCH. b) PDS spectra of several high-mobility polymers. Solid lines in inset represent exponential fits to determine the Urbach energy. Reproduced with permission from ref⁹. Copyright 2014, Springer Nature Ltd.

1122

1123 6.3. Scanning Probe Methods

1124 Scanning probe techniques such as electric force microscopy (EFM) and Kelvin probe
 1125 force microscopy (KPFM) provide high spatial resolution imaging and map the topography of a
 1126 surface by detecting changes in the local contact potential.²³⁷ Trapped charge carriers modify the
 1127 local contact potential and hence these techniques provide an excellent tool to determine the
 1128 origin of traps as well as their spatial distribution. Both KPFM and EFM have been widely used
 1129 to investigate the role of grain boundaries on charge carrier trapping in organic thin films.^{64,65,67}
 1130 Recently, KPFM was used to identify crystal step edges as sources of traps for electrons in single

1131 crystals of n-type semiconductor Cl₂-NDI.⁵⁵ KPFM performed on a rubrene derivative revealed
1132 planar defects resulting from a solid-solid phase transition during cooling.²³⁸ Such defects cause
1133 electronic disorder that could potentially introduce charge carrier traps. Mathijssen et al. studied
1134 the dynamics of trap formation in OFETs upon exposure to ambient conditions. They found that
1135 bias-stress effects were caused by water-related traps originating at the SiO₂ dielectric surface
1136 rather than in the OSC.¹³³ Dougherty and coworkers used KPFM images to map the fluctuations
1137 in surface potential in the transistor channel of an ultrathin α -sexithiophene (α -6T) OFET arising
1138 from trapping and de-trapping of charge carrier from shallow traps.²³⁹ They showed that the
1139 spatial distribution of these fluctuations is uniform throughout the active channel.

1140 Various other techniques can be useful in the detection of traps. For example, micro
1141 Raman imaging has been adopted to detect the coexistence of isomers in diF-TES ADT films,²⁴⁰
1142 which has been previously reported to create a discrete trap state in the same material.²⁰⁵ X-ray
1143 based techniques such as wide angle X-ray scattering (WAXS), small angle X-ray scattering
1144 (SAXS) and resonant soft X-ray scattering and reflectivity (r-SoXS/R) have been used to identify
1145 structural defects, grain boundaries, interface roughness in several OSCs which also serve as
1146 potential charge carrier traps.²⁴¹ Evidence for electrochemical trapping of electrons by silanol
1147 groups in the SiO₂ dielectric has been acquired using multiple-reflection attenuated-total-
1148 reflection Fourier transformed infrared (ATR-FTIR) spectrometry.⁹⁶

1149

1150 7. Exploitation of charge carrier traps for organic sensing devices

1151 While traps are typically regarded as an obstacle to achieving high performance in
1152 organic electronic devices, they can also be exploited towards sensing any factors that can

1153 modulate the trap DOS spectra, e.g. impurities (chemical and biological), temperature, light, or
1154 radiation. The generation or passivation of charge carrier traps in OFET causes a measurable
1155 change in the device performance and hence imparts the sensing mechanism. These changes may
1156 be harnessed to detect chemical, biological or physical agents. Sensors based on OFETs have
1157 several advantages, including biocompatibility, ease of processing, and versatility in molecular
1158 design to address the sensitivity and selectivity challenges well beyond the capabilities of sensors
1159 made from inorganic materials.^{242–246} This section will provide a review of chemical, thermal and
1160 radiation sensors that take advantage of charge trapping/de-trapping to perform sensing
1161 operations.

1162

1163 **7.1. Chemical sensors**

1164 The sensitivity of OSCs to environmental molecules, i.e. ‘analytes’, make them excellent
1165 candidates for gas sensing and odor analysis. These analytes can interact with an OSC through
1166 hydrogen bonding and π interactions, or through reversible and irreversible chemical
1167 reactions.²⁴⁷ These interactions may occur within the bulk of the material, at grain boundaries, or
1168 at device interfaces (metal/semiconductor, or semiconductor/dielectric).²⁴⁸ Chemical sensing
1169 with OFETs can be quite complicated, as there are diverse mechanisms by which the OSC
1170 interacts with chemicals. This section will focus on sensing mechanisms which depend on trap
1171 formation, but there can be other, non-trap related effects that have been exploited for sensing
1172 with OFETs. For an in-depth description of chemical sensing with OFETs, we refer the reader to
1173 several thorough reviews on the subject.^{242,243,249,250}

1174 Using OFETs as the active element in chemical sensors allows for a greater range of
1175 response than equivalent two-terminal devices, since chemical changes can affect the mobility,
1176 threshold voltage, or the on/off current ratio.²⁵¹ One method of sensing relies on the interaction
1177 of polar analytes with the OSC. When the OFET is exposed to a polar analyte, the dipolar
1178 molecules induce local variations in the electric fields in the OSC. Depending on the energy
1179 levels of the analyte with respect to the OSC, trap states can be introduced causing mobile
1180 charges to be localized on the analyte, resulting in a lowering of the drain current or a shift in the
1181 threshold voltage.²⁴² These effects are mediated by the processes occurring at the grain
1182 boundaries, where the disorder leads to an increased polarizability of charge carriers. The density
1183 of grain boundaries is related to the sensitivity of devices to analytes; polar analytes trap charges
1184 at the grain boundaries, localizing charges in tail states, resulting in a lower overall current, and
1185 the response is greater upon increasing the polarity of molecules.^{252,253} The seemingly unlimited
1186 choices of OSCs offer excellent tunability to different analytes,^{253,254} and could be integrated into
1187 electronic noses,²⁵⁵ which can be used to detect, analyze, and identify odors in many
1188 applications. Assuming that each analyte interacts with a given OSC in a distinct way, its
1189 presence and concentration may be identified by measuring the change in operation of the
1190 device, allowing circuits composed of multiple different OSCs to detect specific analytes. These
1191 devices could be implemented in analyzing food freshness by sensing propanol and acetic
1192 acid,²⁵⁵ in identifying traces of explosives²⁵⁶ and nerve gas,²⁵⁷ and detecting hazardous chemicals
1193 in work environments, at parts per million level, or below.^{258,259}

1194 Depending on the nature of the analyte, changes to the OSC film can be reversible or
1195 irreversible: highly reactive gases, such as NO₂, cause irreversible changes to films through
1196 chemisorption, but this can be healed via a high temperature annealing step, as shown in a copper

1197 phthalocyanine device.²⁴⁷ Ammonia gas (NH₃) is an example of a polar analyte which can be
1198 reversibly sensed using OFETs, since it desorbs from the surface once the gas is removed from
1199 the environment. Ammonia sensing is also in high demand as it is a highly toxic and corrosive
1200 agent, and due to its ubiquitous use in industrial and agricultural settings. Katz and coworkers
1201 demonstrated an OFET based on poly (3,3''-didodecylquaterthiophene) (PQT-12) with a
1202 sensitivity of 0.5 ppm when exposed to ammonia, and more recently showed that this effect is
1203 exhibited in both n-type and p-type OSCs, 2,20 - [(2,5-dihexadecyl-3,6-dioxo-2,3,5,6-
1204 tetrahydropyrrolo- [3,4-c] pyrrole-1,4-diylidene) dithiene-5,2-diylidene] dimalononitrile
1205 (DPPCN) and P3HT, respectively.^{260,261} In addition to a high sensitivity, these devices exhibited
1206 a high selectivity to ammonia, and a memory effect when cooled. Adsorption of ammonia onto
1207 the surface of the semiconductor induced energetic disorder and charge - dipole interactions,
1208 which resulted in a decrease in the drain current of the device. By a similar route, adsorption of
1209 ammonia onto spray-coated TIPS pentacene caused a threshold voltage shift, and a decrease in
1210 mobility and drain current.²⁴⁸ Ethanol was detected using pentacene OFETs by studying the
1211 temperature dependence of mobility; the authors showed that exposure to ethanol vapors
1212 increases the activation energy, indicating that charges are deeply trapped when the vapor is
1213 introduced.²⁶²

1214

1215 7.2. Temperature Sensors

1216 The development of small, light-weight, and biocompatible temperature sensors has the
1217 potential to revolutionize the medical field. Temperature and pressure sensing has been achieved
1218 through the use of OFETs coupled with capacitive elements, such as a microstructured PDMS,²⁶³
1219 or by using piezoelectrics as sensing elements, in series with the gate of an OFET.^{264,265} More

1220 recently, temperature sensing relying on trapping allowed for the entire sensor to be contained
1221 within a single OFET device, without additional hardware or processing, offering a clear
1222 advantage over the more complicated and bulky capacitance-based devices.

1223 As discussed in Section 5, the temperature dependence of mobility is strongly related to
1224 the density and distribution (both energetic and spatial) of traps. Strategic choices of dielectric
1225 materials can be used to impart a greater range of thermal sensitivity and expand the sensor use.
1226 For example, OFETs based on dielectrics with strong polar groups, such as polyactide (PLA),
1227 have a high trap density (both deep and shallow) at the semiconductor/dielectric interface.²⁴⁵ By
1228 adding heat into the system, carriers are released from traps, and the threshold voltage showed a
1229 sensitivity of ~ 0.25 V/K, with a nearly linear response, making this is a viable method to
1230 creating temperature sensors. In addition to imparting temperature sensitivity beyond room
1231 temperature, PLA is biocompatible, making it an appealing material for use in medical
1232 applications. This strategy has also been employed using other polar dielectrics, such as poly-
1233 (vinyl alcohol) with a copper phthalocyanine (CuPc) semiconductor, which exhibited a similar
1234 temperature response above room temperature, with reversible changes in device operation.²⁶⁶
1235 More recent work has shown that different metal atoms can impart metal phthalocyanines with
1236 an increased response to temperature, such as Mg and Fe, without the use of a polar dielectric
1237 layer, which could lead to simpler fabrication techniques than dielectric modification.²⁶⁷

1238

1239 **7.3. Light/Radiation sensors**

1240 Photodetectors and radiation detectors based on OSCs are very appealing; their
1241 biocompatibility and conformability make them useful in applications ranging from medical

1242 research, such as sensors attached to the skin,^{246,268} to industrial applications.²⁶⁹ This section will
1243 focus on near-infrared (NIR), visible light, ultra-violet (UV), and high-energy radiation sensors
1244 which rely on charge trapping.

1245 When incident photons are absorbed into the OSC, an exciton is created, which then
1246 diffuses through the OSC until reaching a trap (e.g. defect, impurity, or surface state) where it
1247 dissociates into a free electron and a hole. Holes and electrons may encounter donor or acceptor-
1248 like traps, respectively, causing an increase in the current density in the channel as well as a shift
1249 in the threshold voltage.²⁷⁰ The sensing mechanism relies on trapping and de-trapping of the
1250 majority or minority carriers, which reduces the recombination rate, thus enhancing the
1251 concentration of one carrier type. The trap sensitivity can be manipulated by choice of the
1252 dielectric, or by utilizing semiconductor blends which strategically increase the trap
1253 density.^{269,271}

1254 Sensing in the near infrared has many potential applications in imaging, night vision,
1255 health diagnosis, and industrial monitoring. One example is a bulk heterojunction of poly (N-
1256 alkyl diketopyrrolo-pyrrole dithienylthieno[3,2-b] thiophene) (DPP-DTT) and PCBM in a
1257 phototransistor configuration. The narrow bandgap and high absorption in the near-infrared make
1258 these materials ideal for NIR sensing. The devices exhibited responsivities of up to $5 \times 10^5 \text{ A W}^{-1}$
1259 ¹, with a gain of $\sim 10^4$, though the responsivity decreases with light intensity due to filling of
1260 longest-lived trap states, leaving the short-lived trap states to dominate the gain effects.²⁷² A
1261 similar strategy was used by Sun et al., who added PbS quantum dots in P3HT thin-film
1262 transistors. In this case the electrons were trapped on the PbS domains, and responsivities up to 2
1263 $\times 10^4 \text{ A W}^{-1}$ were achieved; for reference neat P3HT showed negligible photoresponse.²⁷³ Qiu, et
1264 al. used bis(2-oxoindolin-3-ylidene)-benzodifuran-dione (PBIBDF-TT) nanowires (PBIBDF-TT

1265 absorbs in the NIR region) to fabricate photodetectors, and recorded the highest sensitivity when
1266 SiO₂ was used as dielectric owing to the high trap density characteristic to these devices.²⁶⁹
1267 Operation in air increased the photoresponse further, and the authors postulated that the high
1268 surface/volume ratio increased the number of trap sites from adsorbed H₂O and O₂, which further
1269 traps photogenerated charges, increasing the photoconductive gain.

1270 Efforts focused on visible light sensing rely primarily on charge trapping at the dielectric
1271 surface.²⁷¹ Park et. al fabricated pentacene FET devices using poly (methyl methacrylate)
1272 (PMMA), poly(4-vinylphenol) (PVP), and Cytop dielectrics, and studied the impact of the
1273 dielectric on photosensitivity: PMMA contains an ester group, which acts as a trapping site for
1274 holes, PVP has electron trapping hydroxyl groups, and Cytop is inert. They found that the FETs
1275 with PVP dielectric showed the greatest photo response and the traps induced a hysteresis effect,
1276 which is useful in memory applications. By increasing the concentration of hydroxyl groups in
1277 the PVP layer, the authors were able to increase the photocurrent and hysteresis effect. While
1278 PMMA and Cytop did not give the hysteresis effect, they still exhibited a mild photoresponse,
1279 which was attributed to trapping at the grain boundaries in the pentacene film. A similar effect
1280 was observed by Kim et al., in inkjet printed α,ω -dihexylquarterthiophene (DH4T) OFETs with a
1281 PVP dielectric: they found that electron trapping shifts the threshold voltage and results in an
1282 increase in the density of photoinduced holes in the channel.²⁷⁴ Polyactide (PLA) dielectrics also
1283 increase photosensitivity by introducing strong polar groups into the dielectric. This dielectric
1284 allowed them to detect light with intensity as low as 0.02 mW cm⁻², with a photosensitivity of
1285 10⁴.²⁷⁵

1286 The detection of UV light often requires the use of filters or waveguides to separate UV
1287 from visible light,²⁷⁶ which increases the complexity of traditional UV sensors. Smithson et al.

1288 demonstrated a sensor which was inert to visible light, and only detected UV radiation, without
1289 the need for complicated waveguides.²⁷⁷ This was achieved by creating a blend of a polymer
1290 binder with strong electron donating amine groups, azobenzene derivative disperse red 1 (*p*-
1291 DR1), and 2,7-dipentyl[1]benzothieno[3,2-*b*][1] benzothiophene (C5-BTBT) and recording the
1292 shift in the threshold voltage as a function of the intensity of the radiation. Huang et. al used an
1293 electret layer, namely a doped triphenylamine (TPA)-based polymer, between the pentacene film
1294 and the dielectric layer, to achieve UV sensing and an UV programmable memory effect. The
1295 electret layer serves a dual function: first, upon UV irradiation, it has an emission peak which
1296 overlaps the absorption peak of pentacene, enhancing exciton creation, and second, it traps
1297 electrons from dissociated excitons, increasing the hole photocurrent. The trapped electrons may
1298 be 'erased' with UV light, serving the memory function, though the responsivity of these devices
1299 was low, at $\sim 45 \text{ A W}^{-1}$.²⁷⁸

1300 Sensing of ionizing radiation (X-rays/ γ -rays), as well as the sensing of charged particles,
1301 such as protons, is a subject of recent attention,^{279,280} owing to the possible applications that they
1302 may enable. While in some devices the sensing mechanism is similar to that used to detect NIR
1303 and visible light, other devices rely on the creation of traps in devices when exposed to radiation.
1304 Batlogg and coworkers showed that proton irradiation of single crystal rubrene created deep trap
1305 states in the crystal, which was attributed to a breaking in the C-H bonds.¹⁴¹ They also showed
1306 that X-ray irradiation causes local disorder in the crystal, a common source of traps in OSCs.²⁸¹
1307 Proton irradiation of TIPS pentacene OFETs resulted in a decrease in device mobility as a result
1308 of the fact that the heavy particles caused structural disorder within the organic film.²⁸² In the
1309 same material, it has been shown that irradiation with X-rays produces a photoconductive gain
1310 effect: the authors attributed this to an increase in the conductivity of the films by the

1311 accumulation of free charge carriers, which act as a dopant.²⁸⁰ Later, they amplified the
1312 photoconductive gain by using a FET configuration and substituting TIPS-pentacene with diF-
1313 TES ADT and diF-TEG ADT. The inclusion of Si and Ge atoms into the molecular structure
1314 provided a high-Z component, which increased the response to high energy photons because of
1315 the high scattering cross section of these atoms.²⁷⁹

1316

1317 **7.4. Memory Devices based on Charge Trapping**

1318 A robust control of the dynamics of charge trapping led to its exploitation in memory
1319 applications; long-lived trap states induce shifts in current-voltage characteristics, and while such
1320 behavior is not desired for a typical device operation (see for example the effects described in
1321 Section 4), it can give rise to discrete memory states. The memory states form the basis for a
1322 variety of applications, from imparting memory capabilities to flexible circuits to mimicking
1323 neurons in neuromorphic circuits for artificial intelligence and deep learning.^{283–287} In synaptic
1324 memory devices, control of the charge trapping was accomplished by doping the OSC with
1325 either non-metallic particles (e.g. ZnO),²⁸⁸ or metallic particles (e.g. Au).²⁸⁹ These particles trap
1326 charges in the conduction channel, therefore altering the device characteristics. Memories based
1327 on this method have long retention times, but need to be ‘read’ by applying a gate voltage, which
1328 can affect the stored memory state.²⁸⁴ Techniques which make use of photochromic molecules,
1329 such as spiropyran, azobenzene, or diarylethene, can overcome this limitation, since the memory
1330 is switching using light, and not the electric field.²⁹⁰ These molecules change their conformation
1331 upon exposure to UV light, which is key to their function as memory devices.^{291,292} For example,
1332 Samorì and coworkers utilized a blend of diarylethene (DAE) photochromic molecules P3HT to
1333 realize a photo-switchable memory device.²⁹³ When the DAE was exposed to UV light, the

1334 isomer 'switched' to the closed state, whose HOMO was within the bandgap of the P3HT, and
1335 therefore acted as a hole trap, reducing the current of the device. The trapping/de-trapping was
1336 highly stable and reversible: DAE molecules revert to the open isomer by exposure to visible
1337 light, and the devices modulated the current continuously, allowing many possible memory
1338 states, imparting organic electronic devices the ability to act as memory devices in complex
1339 circuits.

1340

1341 **8. Summary and future perspectives:**

1342 Charge carrier trapping is ubiquitous in OSCs and is a direct consequence of van der
1343 Waals intermolecular interactions inherent in these materials. The details on the nature, spatial
1344 and energetic distribution of traps, as well as timescales of trapping/de-trapping events, have a
1345 profound impact on the performance of organic electronic devices. Studies related to the subject
1346 date back to the 1960s, when the research focused almost exclusively on free standing molecular
1347 crystals.^{33,34,54} Later, the effort was expanded to address charge carrier trapping occurring in thin
1348 films and at device interfaces. Tail states introduced by dynamic disorder arising from thermal
1349 motions and their role in charge carrier trapping have also recently garnered attention. In this
1350 review, we aimed to provide readers with a comprehensive overview on the phenomenon of
1351 charge carrier trapping in OSC materials and opto-electronic devices. Beginning with the
1352 definition of traps, we then discussed their origin and properties, categorized the sources of traps
1353 in OSCs and provided examples for each case. Sources of traps range from structural defects to
1354 chemical impurities, from devices interfaces to environmental effects, with many of these effects
1355 being coupled. A discussion on the impact of charge carrier trapping on the mechanism of charge
1356 transport and the performance of organic electronic devices was provided, including strategies

1357 adopted to mitigate these effects for optimal device function. Next, we discussed the
1358 experimental techniques available for the detection and characterization of traps. Optical and
1359 thermal methods rely on radiative and non-radiative electronic transitions between localized
1360 band gap states enabling the extraction of trap parameters, with thermal methods having the
1361 potential of probing deeper band gap states. Electrical measurements in device configurations
1362 such as OFETs and two terminal devices serve as excellent tools to extract energetic distribution
1363 of traps, while scanning probe techniques are useful in determining the spatial distribution of
1364 traps. Applications such as chemical, temperature and radiation sensors, in which the
1365 phenomenon of charge carrier trapping is exploited for detection were briefly discussed.

1366 Remarkable progress has been made over the years in terms of characterization of traps,
1367 clarifying the impact on charge transport and reducing undesirable effects through innovations in
1368 material design and device fabrication. Increasingly better understanding of the phenomenon has
1369 led to new design rules for organic devices, and made the reduction in the density of charge
1370 carrier traps possible. For example, OSCs with an ionization energy of less than 6 eV and an
1371 electron affinity greater than 3.6 eV are predicted to yield trap-free charge transport of both holes
1372 and electrons, which is an important milestone achieved that can subsequently enhance device
1373 performance to a great extent.⁸⁶ Despite the numerous efforts, unanswered questions still persist.
1374 Most methods for trap characterization are indirect and require different levels of
1375 approximations, often making the interpretation of results difficult. Systematic studies involving
1376 deliberate incorporation of traps to investigate their effect on the DOS spectrum are rare. Access
1377 to each source of trap independently would clarify its impact on charge transport, but this is
1378 practically impossible because many trapping events are correlated (e.g. an impurity generates
1379 energetic as well as structural disorder). In addition, studying the dynamics of trap states is

1380 another challenging direction of future research. Elucidating the time evolution of trap states will
1381 aid in comprehending the effect of dynamic disorder, the major performance-limiting factor in
1382 electronic devices. Resolving these issues, coupled with progress in understanding and
1383 enhancing charge injection, development of new materials, and optimizing device structure, will
1384 lead to significant improvements in the performance of electronic devices, enabling their full
1385 potential to be realized in real-world applications.

1386 **Acknowledgements:**

1387 This work was supported by the National Science Foundation through Grant Nos. DMR-
1388 1627925 and ECCS- 1810273.

1389 **Conflicts of interest:**

1390 The authors declare no conflicts of interest.

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The phenomenon of charge carrier trapping in organic semiconductors and their impact on electronic devices are reviewed

